



# LOCAL, ABSOLUTE RESIDUAL STRAIN MEASUREMENTS USING COMBINED RING-CORE MILLING AND CROSS-CORRELATION EBSD IN AN SEM

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# Contents



- Residual stresses (RS) – why, what, how?
- Measurement of RS by cross-correlation  
CC-EBSD
- The measurement principles of ring core  
milling (RCM)
- Absolute measurement of RS by combination  
of CC EBSD and RCM
- Conclusions

# Contents

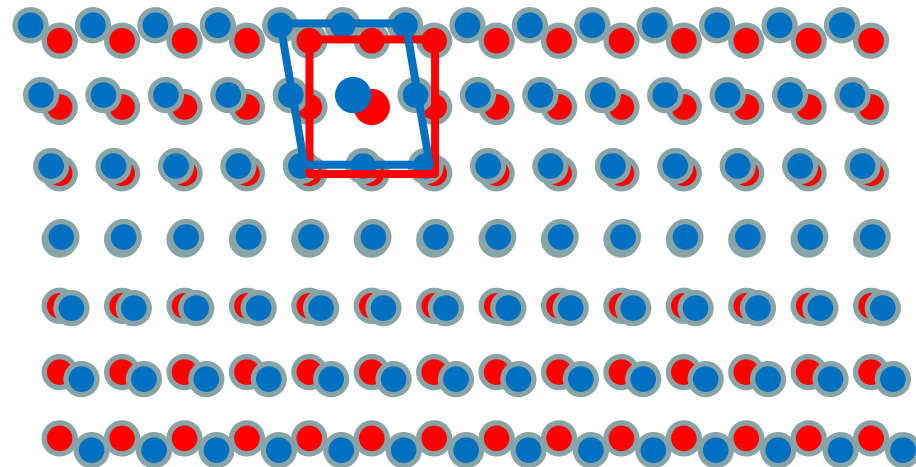


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# What are residual stresses?

- Elastic strains:
  - long range deviation of atom positions from their positions taken without presence of external forces while keeping their local neighborhood.



- Elastic stresses:
  - Forces that act to bring atoms back to their equilibrium positions according to Hook's law



# Residual stresses, mathematical description

- Elastic strains:

$$\boldsymbol{\epsilon} = \begin{pmatrix} \epsilon_{11} & \epsilon_{12} & \epsilon_{13} \\ \epsilon_{21} & \epsilon_{22} & \epsilon_{23} \\ \epsilon_{31} & \epsilon_{32} & \epsilon_{33} \end{pmatrix}$$

- Hook's law:

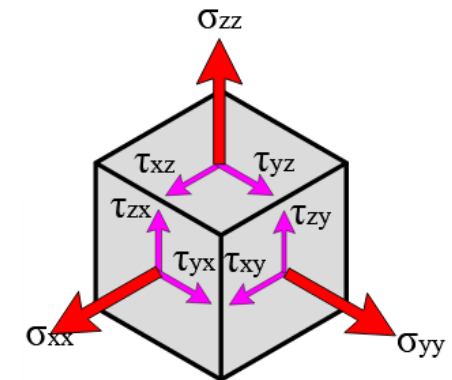
$$\boldsymbol{\sigma} = \mathbf{E}\boldsymbol{\epsilon}$$

- Elastic stresses:

$$\boldsymbol{\sigma} = \begin{pmatrix} \sigma_{11} & \sigma_{12} & \sigma_{13} \\ \sigma_{21} & \sigma_{22} & \sigma_{23} \\ \sigma_{31} & \sigma_{32} & \sigma_{33} \end{pmatrix}$$

normal stresses

deviatoric stresses



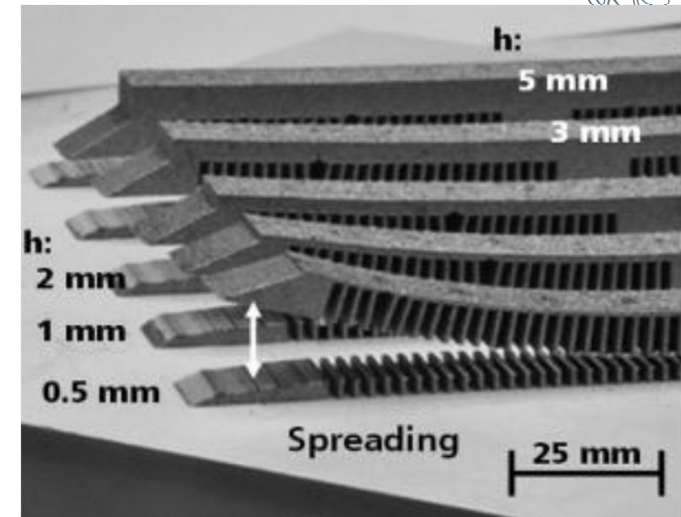
- von-Mises equivalent stress (1 represents all)

$$\sigma_{vM} = \sqrt{\sigma_{11}^2 + \sigma_{22}^2 + \sigma_{33}^2 - \sigma_{11}\sigma_{22} - \sigma_{11}\sigma_{33} - \sigma_{22}\sigma_{33} + 3(\sigma_{12}^2 + \sigma_{13}^2 + \sigma_{23}^2)}$$



# Residual stresses – why care?

- Shape accuracy during/after mechanical forming or additive manufacturing
- Fracture nucleation (e.g. in martensitic structures)
- Crack growth
- Mechanical properties (e.g. Bauschinger effect)
- Stress corrosion cracking
- Hydrogen embrittlement
- Electronic effects



C. Li et al. *Procedia CIRP* 71 (2018) 348–353



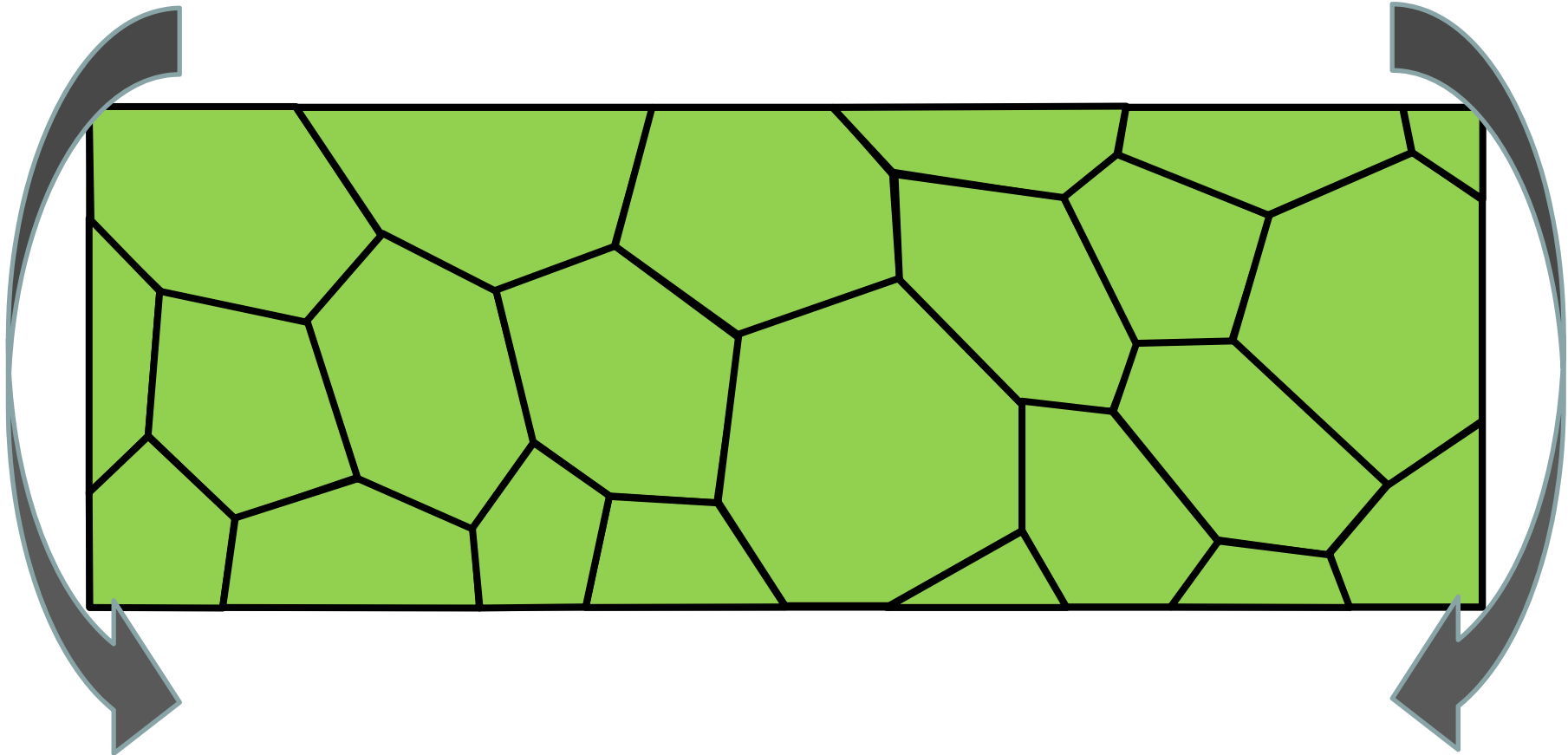
S. Papula et al., *Met. Mat. Trans. A* 45 (2014), 5270

Review by Koyama et al: *Int. J. Hydrogen Energy* 42 (2017) 12706



# Classification of residual stresses

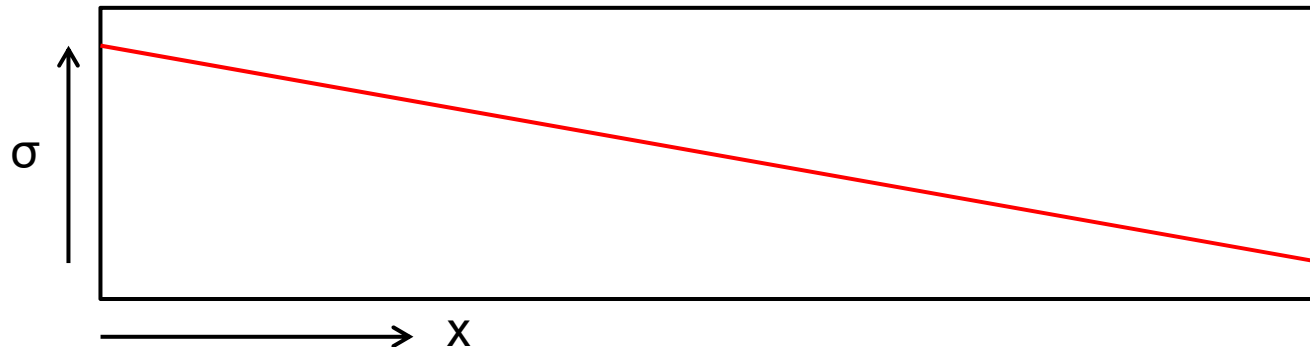
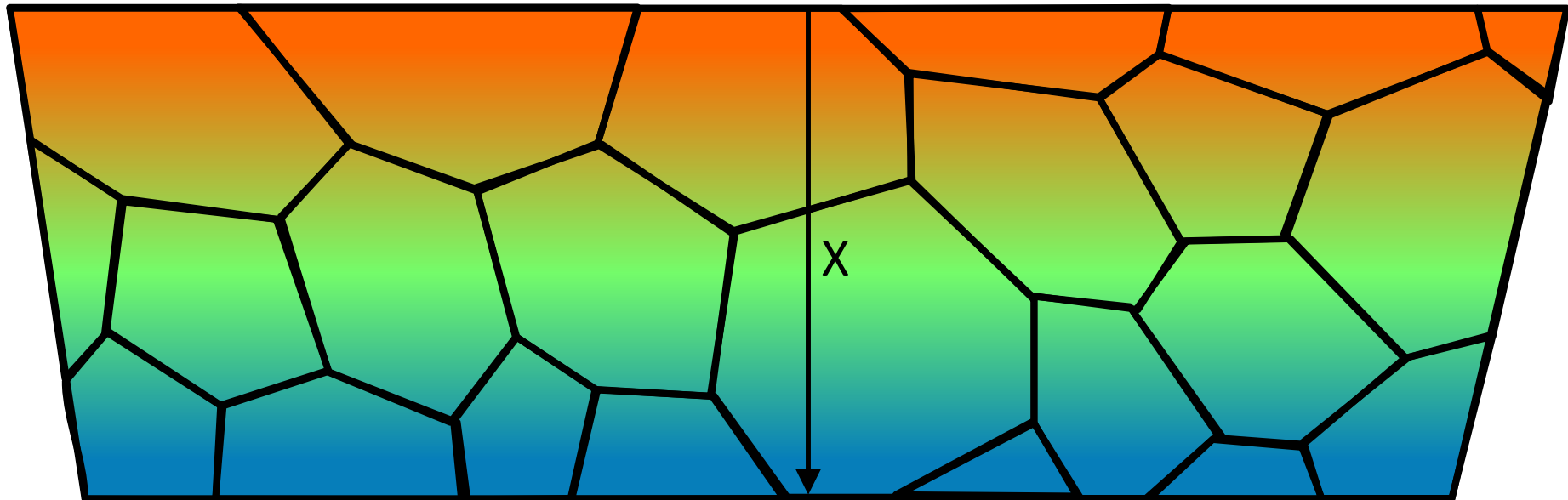
Stress-free





# Classification of residual stresses

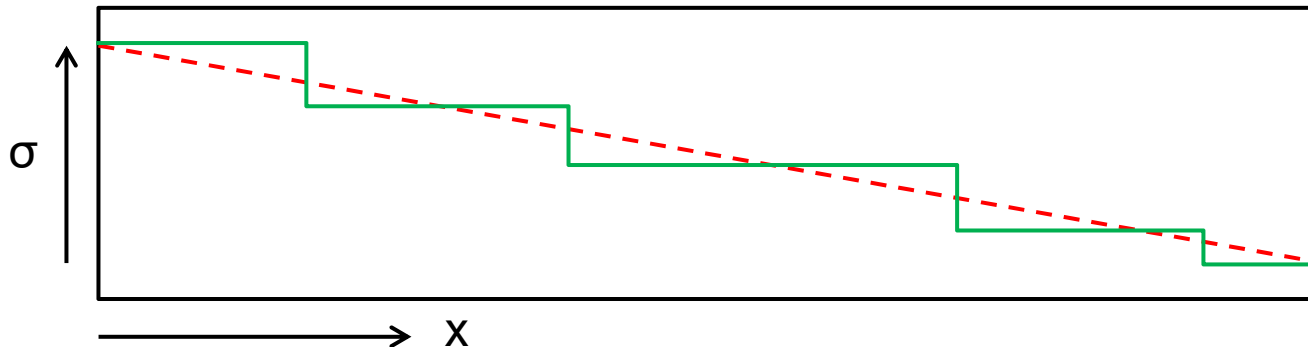
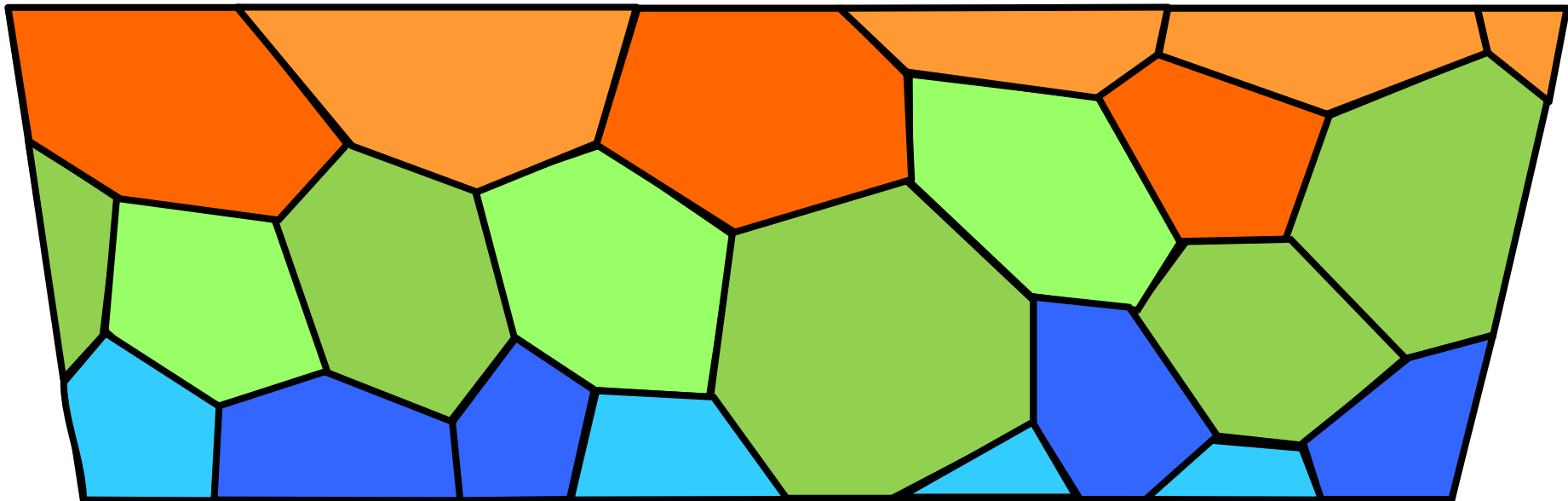
Stresses of 1<sup>st</sup> kind (macroscopic stresses)



# Classification of residual stresses



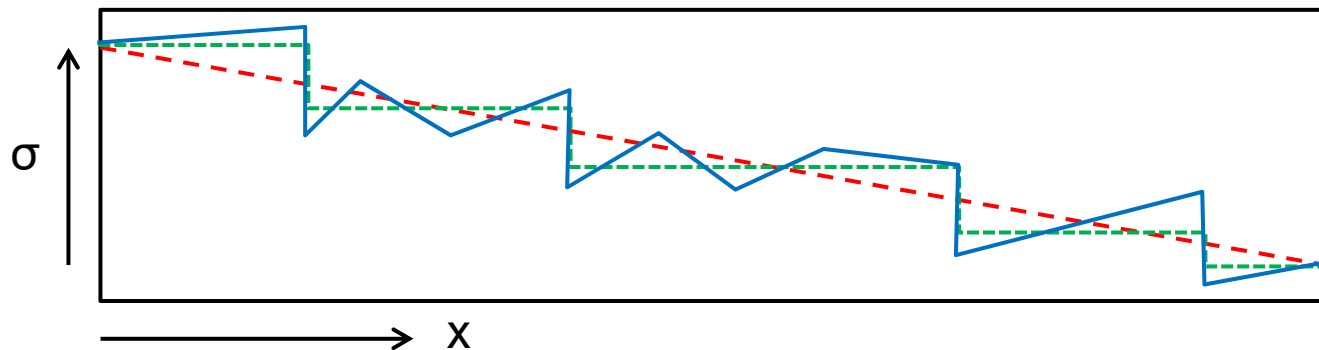
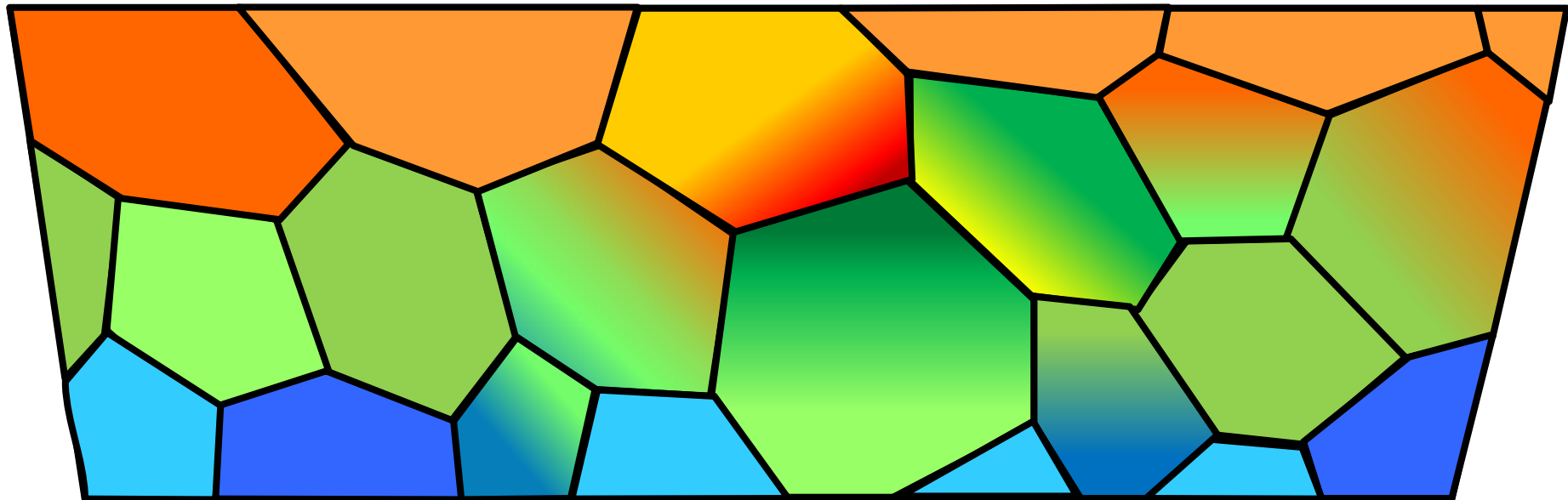
Stresses of 2<sup>nd</sup> kind (grain-to-grain stresses)





# Classification of residual stresses

Stresses of 3<sup>rd</sup> kind (grain-internal stresses)



# Measurement of residual stresses



Type	Techniques	Measured parameter	Measured quantities	Spatial resolution	Accuracy (limited by)	Type of evaluated stress	Comments
	Beam deflection		Beam deflection vs. coating thickness	0.05 of thickness; no lateral resolution	Limited by minimum measurable curvature		
Mechanical	Slit / Hole drilling	Distortion caused by stress relaxation	Released strain	50 $\mu\text{m}$ in depth	$\pm 50$ MPa (reduced sensitivity with increasing depth)	Type 1	Measure in-plane stresses
	Ring core milling			<b>1 <math>\mu\text{m}</math></b>	<b><math>10^{-3}</math> ??</b>	Types 1, 2	
	X-rays $\sin^2 \psi$			1 mm laterally, 20 $\mu\text{m}$ in depth	$\pm 20$ MPa (texture, surface condition)	Peak shifts: types 1, 2	Sensitive to surface preparation
Diffraction-based	Hard X-rays			20 $\mu\text{m}$ lateral to incident beam; 1 mm parallel to beam	$\pm 10^{-5}$ strain (grain sampling statistics)	Peak widths: types 2, 3	spotty powder patterns
	Neutrons	Atomic strain gauge	Diffraction angles	500 $\mu\text{m}$	$\pm 5 \times 10^{-5}$ strain (counting statistics and reliability of stress free ref.)	Types 1, 2	Difficult to access, costly
	Electrons (EBSD)			100 nm	$10^{-4}$	Type 3	
Ultrasonic	Acousto-elasticity	Stress related changes in elastic wave velocity	Wave velocities	5 mm	10%	Types 1, 2, 3	Microstructure sensitive
Magnetic	Barkhausen noise	Variations in magnetic domains with stress	Magnetic Barkhausen noise	1 mm	10%	Types 1, 2, 3	

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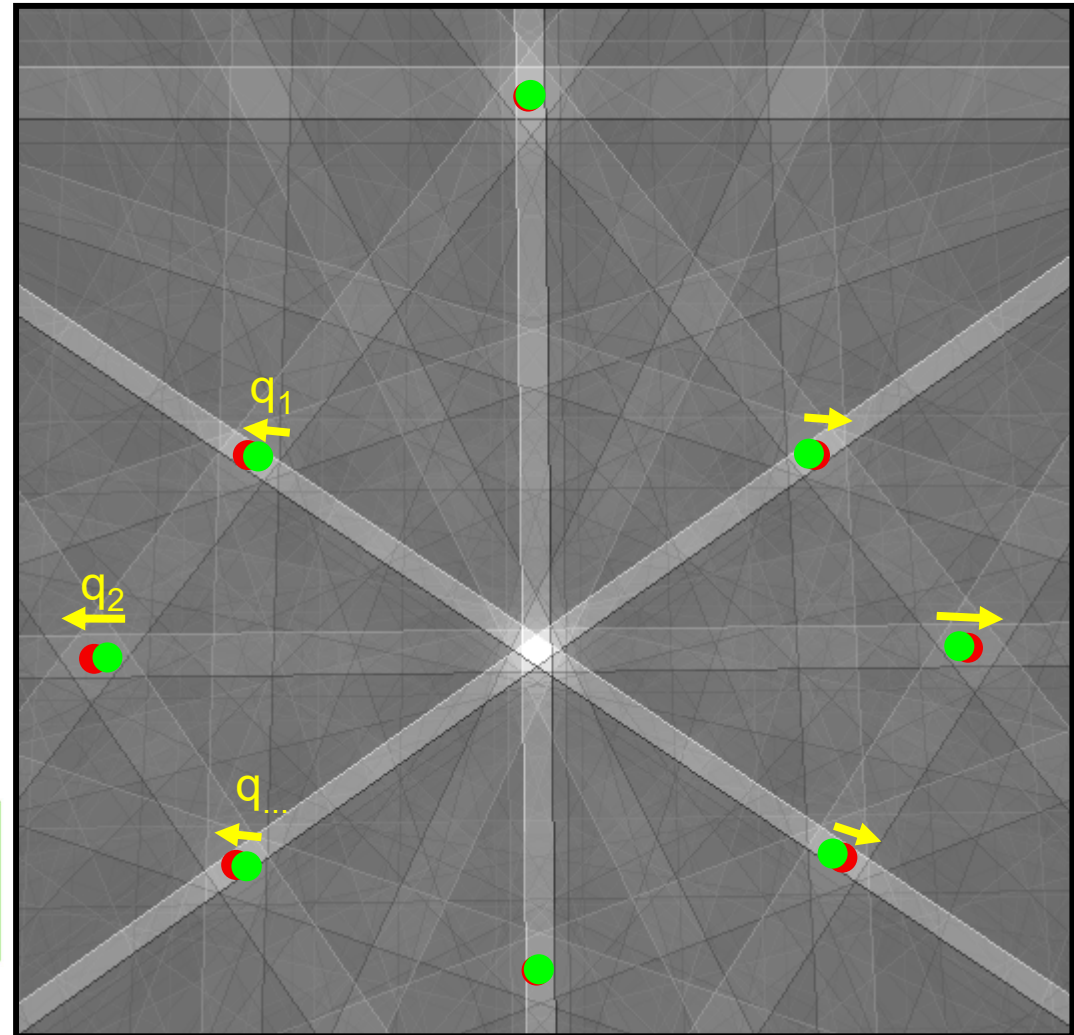
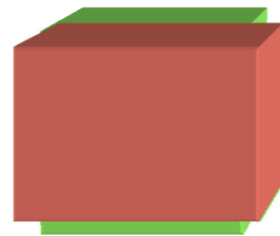
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# Cross-correlation EBSD pattern analysis

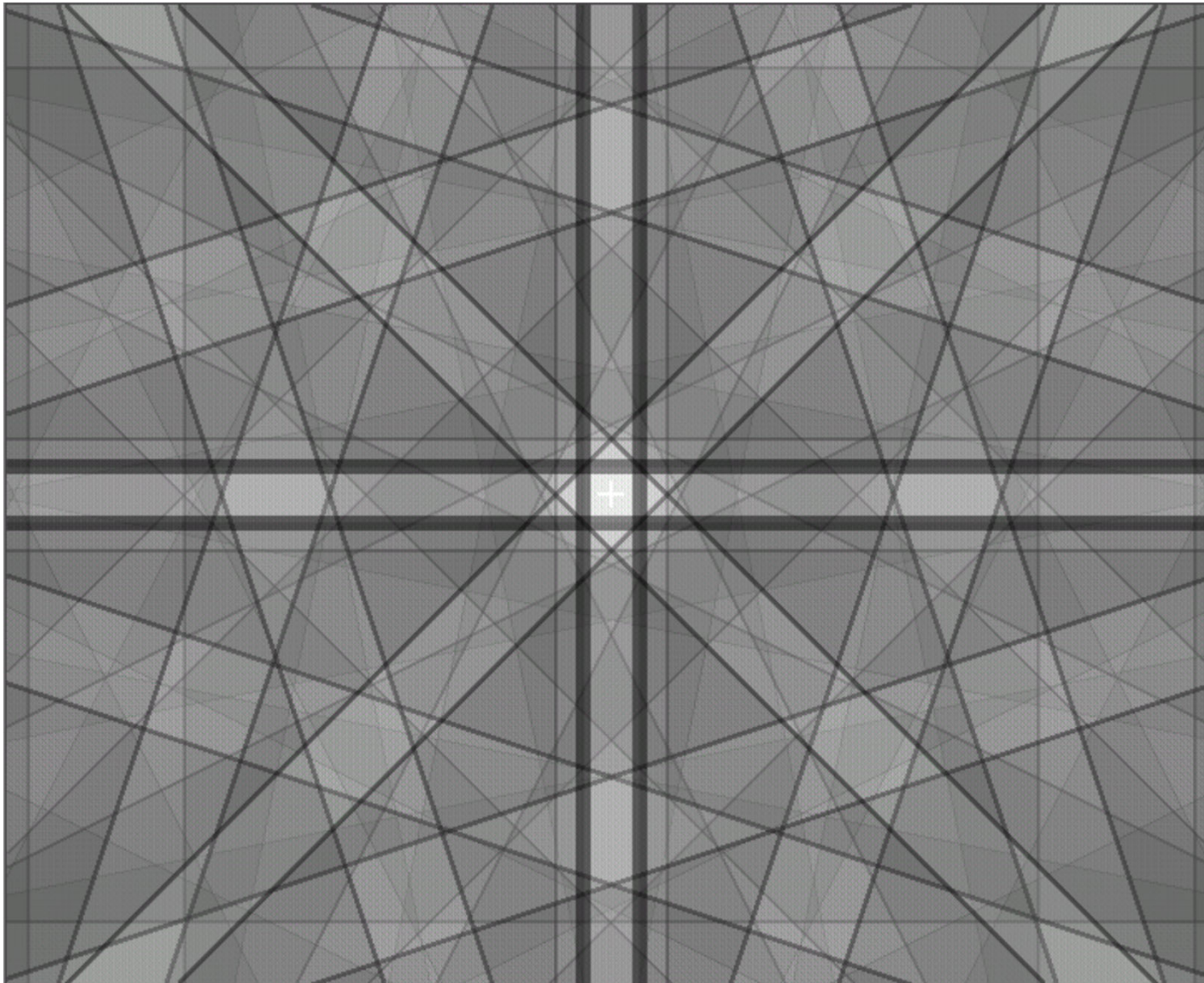
## Basic idea:

- Crystal lattice and diffraction patterns get distorted by the action of an external stress
- Note: hydrostatic part of stress tensor only changes width of Kikuchi bands → cannot be detected accurately
- only deviatoric part of stress tensor can be measured



e.g. Wilkinson, Meaden, Dingley, Ultramicroscopy 106 (2006) 307

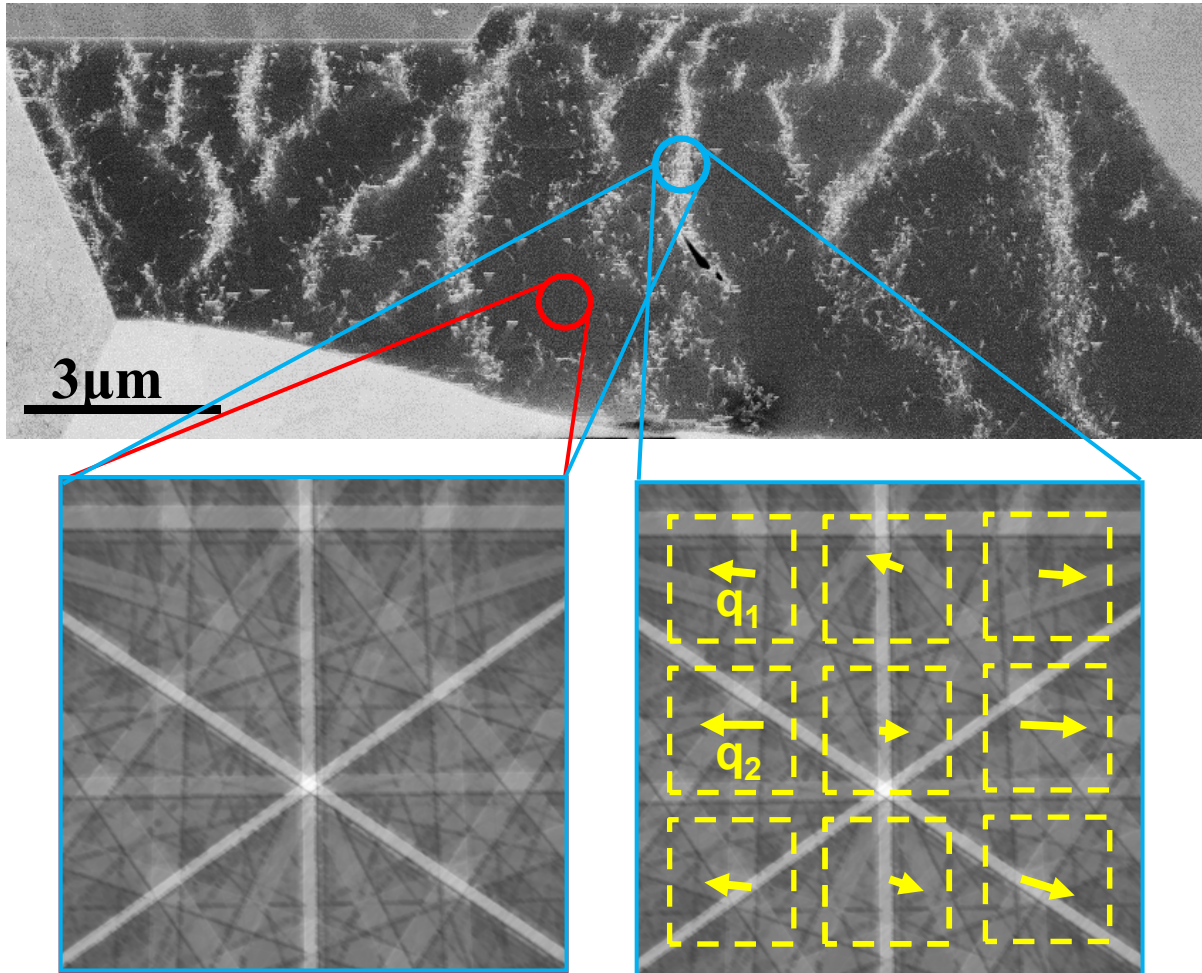
# Determination of elastic strain by EBSD



Example: 0.2% of lattice strain (simulated on an fcc lattice)



# Cross-correlation EBSD for stress and strain measurement



Calculation of displacement gradient tensor  $\mathbf{A}$  from measured shift vectors  $\mathbf{q}^*$

$$\mathbf{A} = \begin{pmatrix} a_{11} & a_{12} & a_{13} \\ a_{21} & a_{22} & a_{23} \\ a_{31} & a_{32} & a_{33} \end{pmatrix}$$

**elastic stretches**  
(symmetric part)

$$\boldsymbol{\varepsilon}_{shear} = \frac{1}{2}(\mathbf{A} + \mathbf{A}^t)$$

**elastic stresses:  $\boldsymbol{\sigma} = \mathbf{E} \boldsymbol{\varepsilon}$**

**crystal rotations**

(anti-symmetric part)

$$\boldsymbol{\omega}_{rotation} = \frac{1}{2}(\mathbf{A} - \mathbf{A}^t)$$

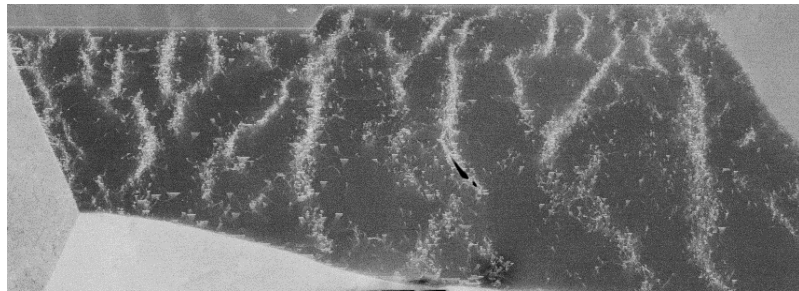
## Accuracy:

Rotations  $\Delta\omega = 0.03^\circ$ , Distortions:  $\Delta\varepsilon = 5 \times 10^{-4}$

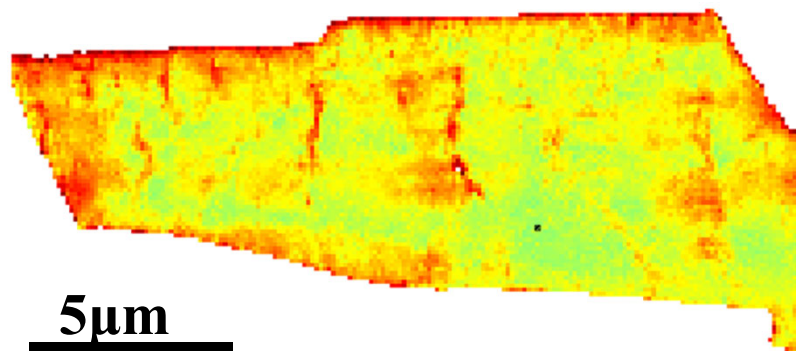
Stresses:  $\Delta\sigma_{ij} = \pm 12 \text{ MPa}$  (for TWIP steels)



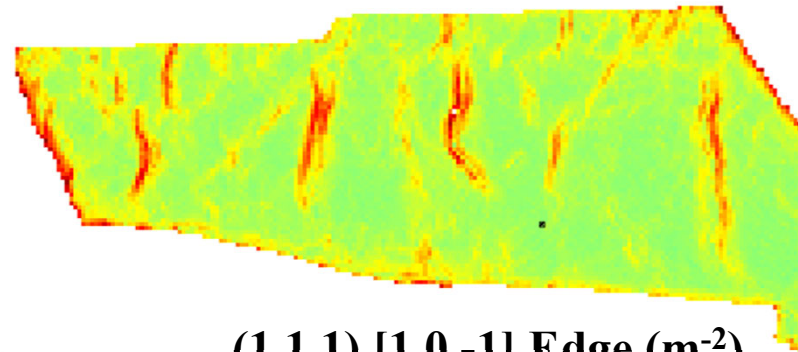
# Stresses and GND densities



Von Mises stress [GPa]



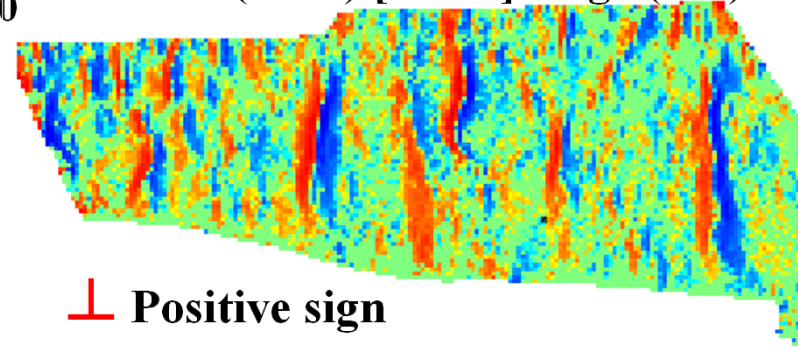
Total GND Density Map ( $\text{m}^{-2}$ )



$5\text{E}+14$

$(1\ 1\ 1)\ [1\ 0\ -1]$  Edge ( $\text{m}^{-2}$ )

0.40



$2\text{E}+14$

$5\text{E}+13$

$1\text{E}+13$

$2\text{E}+12$

$5\text{E}+11$

0

$-5\text{E}+11$

$-2\text{E}+12$

$-1\text{E}+13$

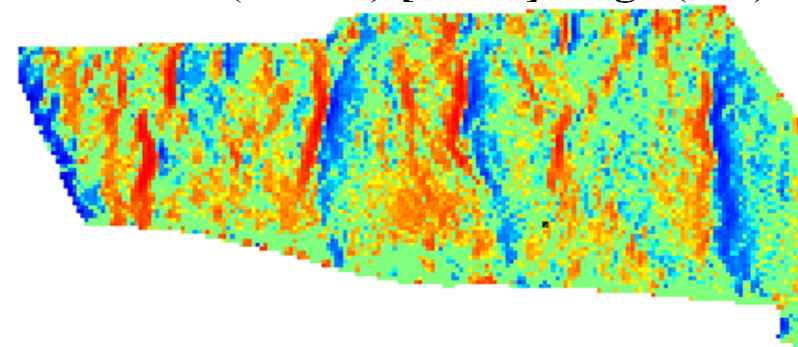
$-5\text{E}+13$

$-2\text{E}+14$

⊥ Positive sign

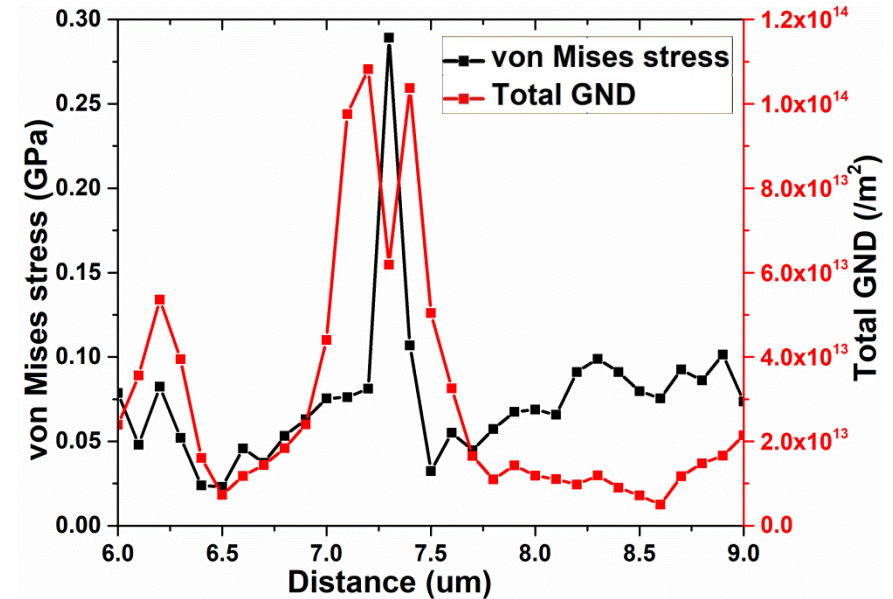
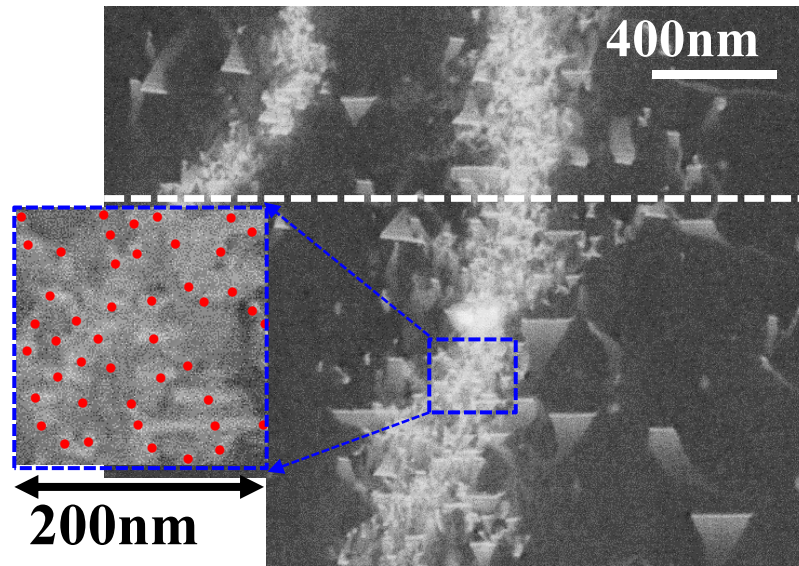
⊥ Negative sign

$(-1\ 1\ -1)\ [-1\ 0\ 1]$  Edge ( $\text{m}^{-2}$ )





# Dislocation wall structure (EBSD & ECCI)



## Dislocation densities:

$$\rho_{\text{total}} = 1.13 \cdot 10^{15} \text{ m}^{-2}$$

$$\rho_{\text{GND}} = 1.17 \cdot 10^{14} \text{ m}^{-2}$$

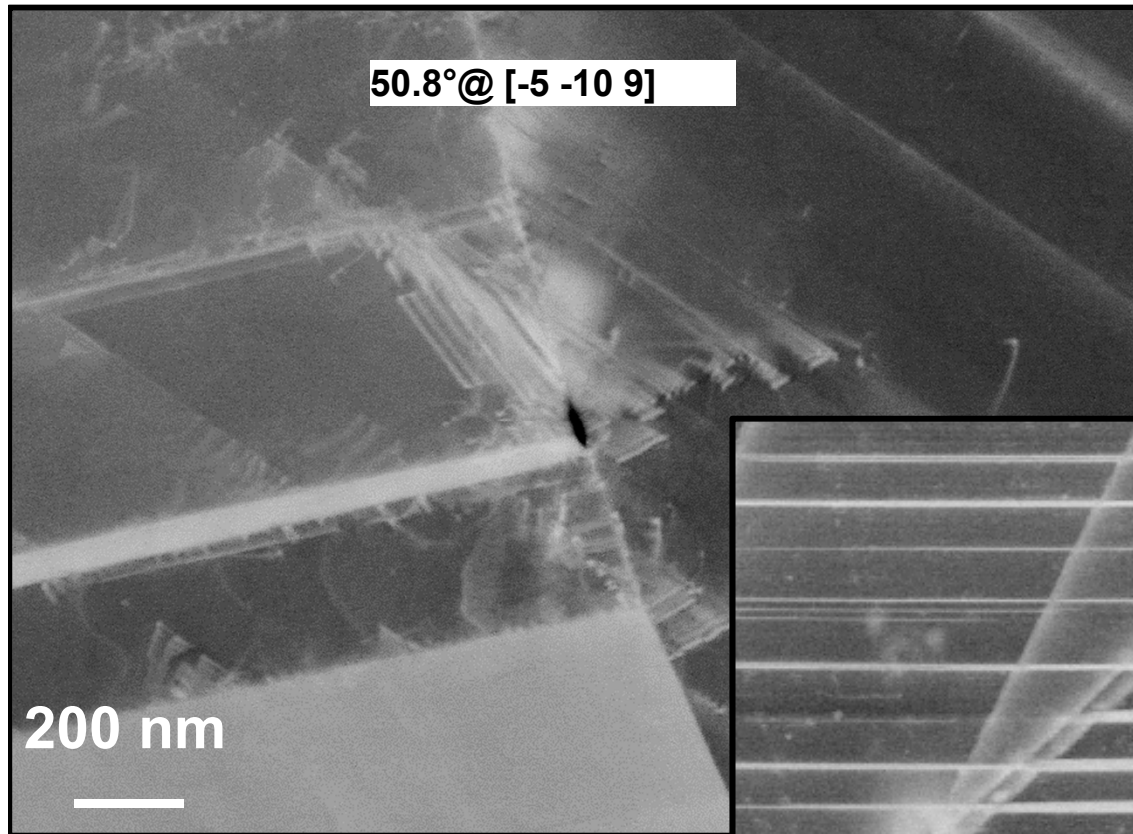


$$\rho_{\text{total}} = 10 \times \rho_{\text{GND}} !$$

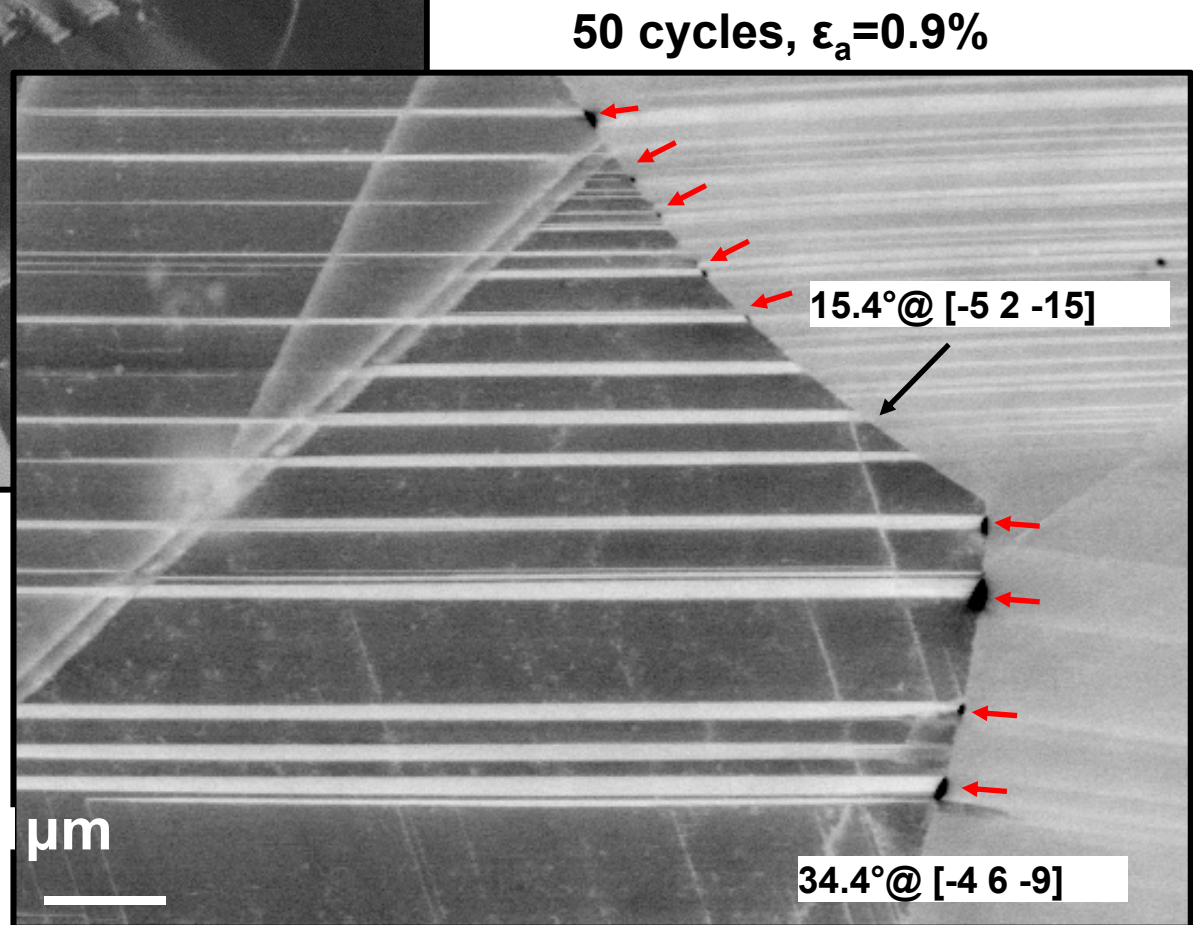
**The main problem with CC EBSD:** a reference pattern from same grain is needed, only strains of 3<sup>rd</sup> kind can be determined



# Crack formation at grain boundaries



5 cycles,  $\epsilon_a=1.1\%$



# CC EBSD: pros and cons



- Mapping technique, potentially with high spatial resolution (EBSD:  $\sim 50 \dots 500$  nm)
- Good strain accuracy ( $\sim 10^{-4}$ )
- Reasonably high rate of measurement ( $\sim 1$  Hz)
- In grains with larger misorientations ( $> 3^\circ$ ): use pattern remapping
- Only measurements of 3rd kind residual stresses
- Results usually in relatively large values  $\rightarrow$  where do they come from?
- Which reference point should be selected?

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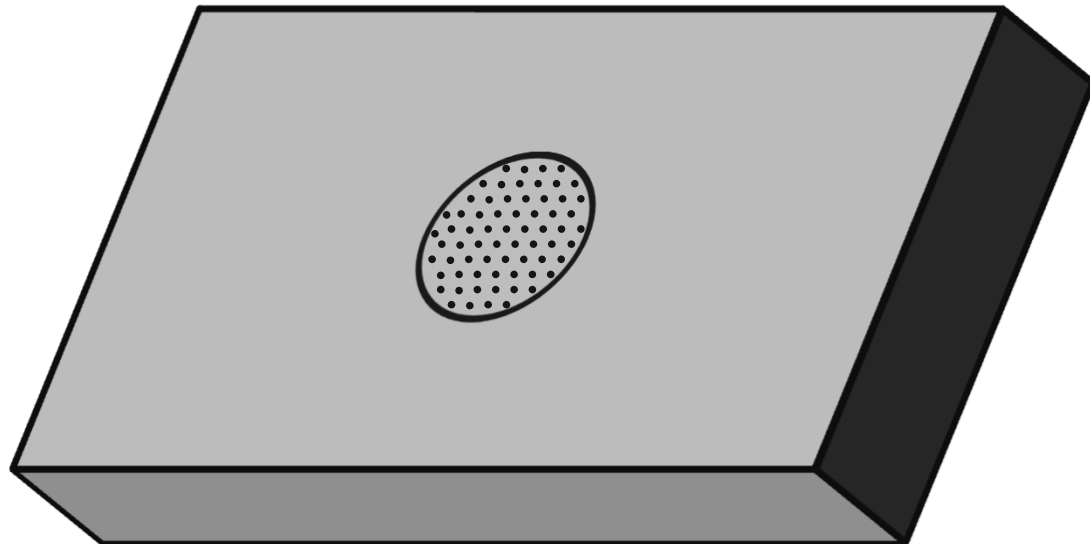
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# Principles of ring-core milling



Residual stress measurement by mechanical relaxation:

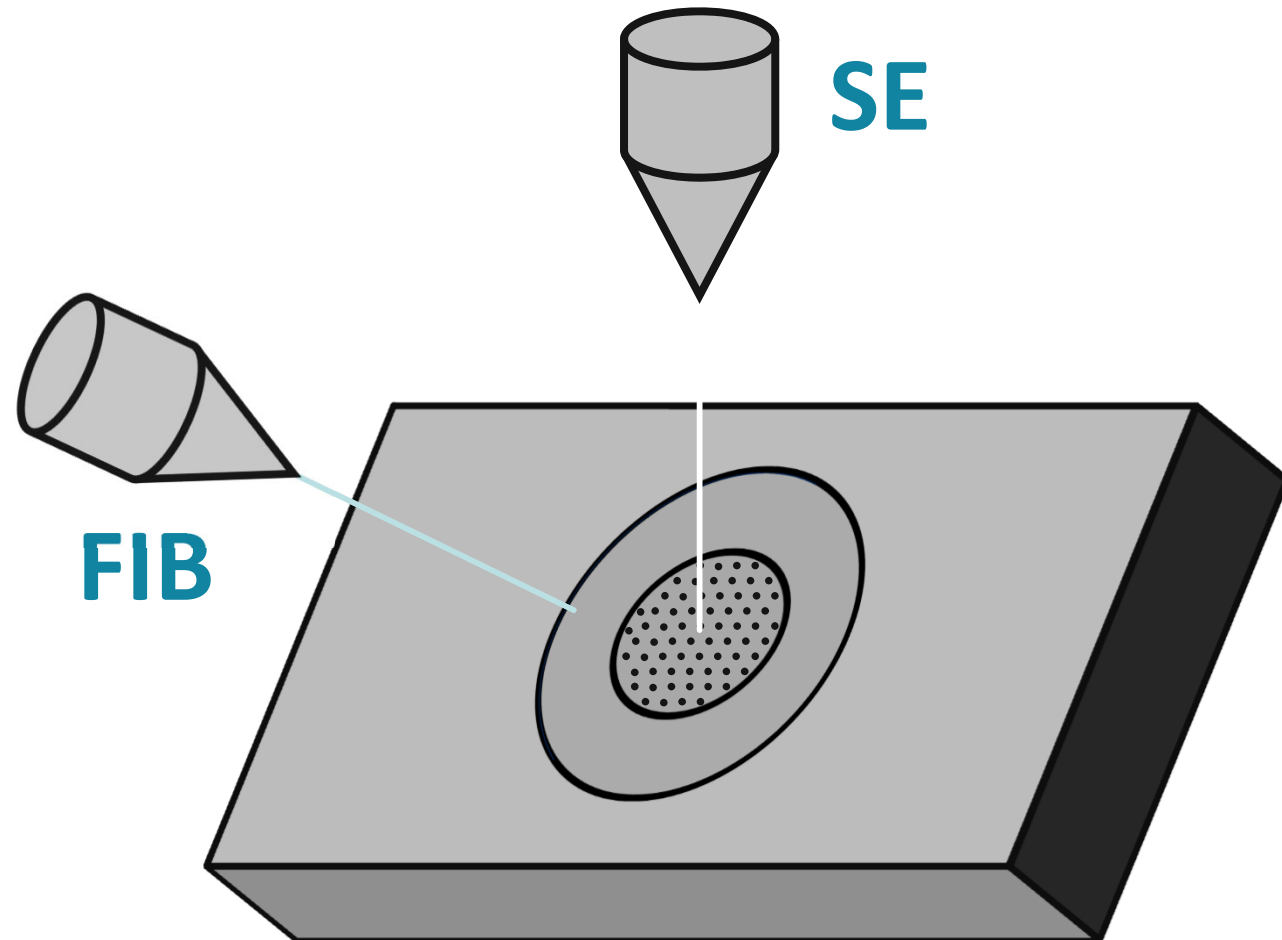
- cut-free a selected area and measure relaxation strains
- enables absolute stress measurements also in heavily defected microstructures
- high spatial resolution if done by FIB sputtering



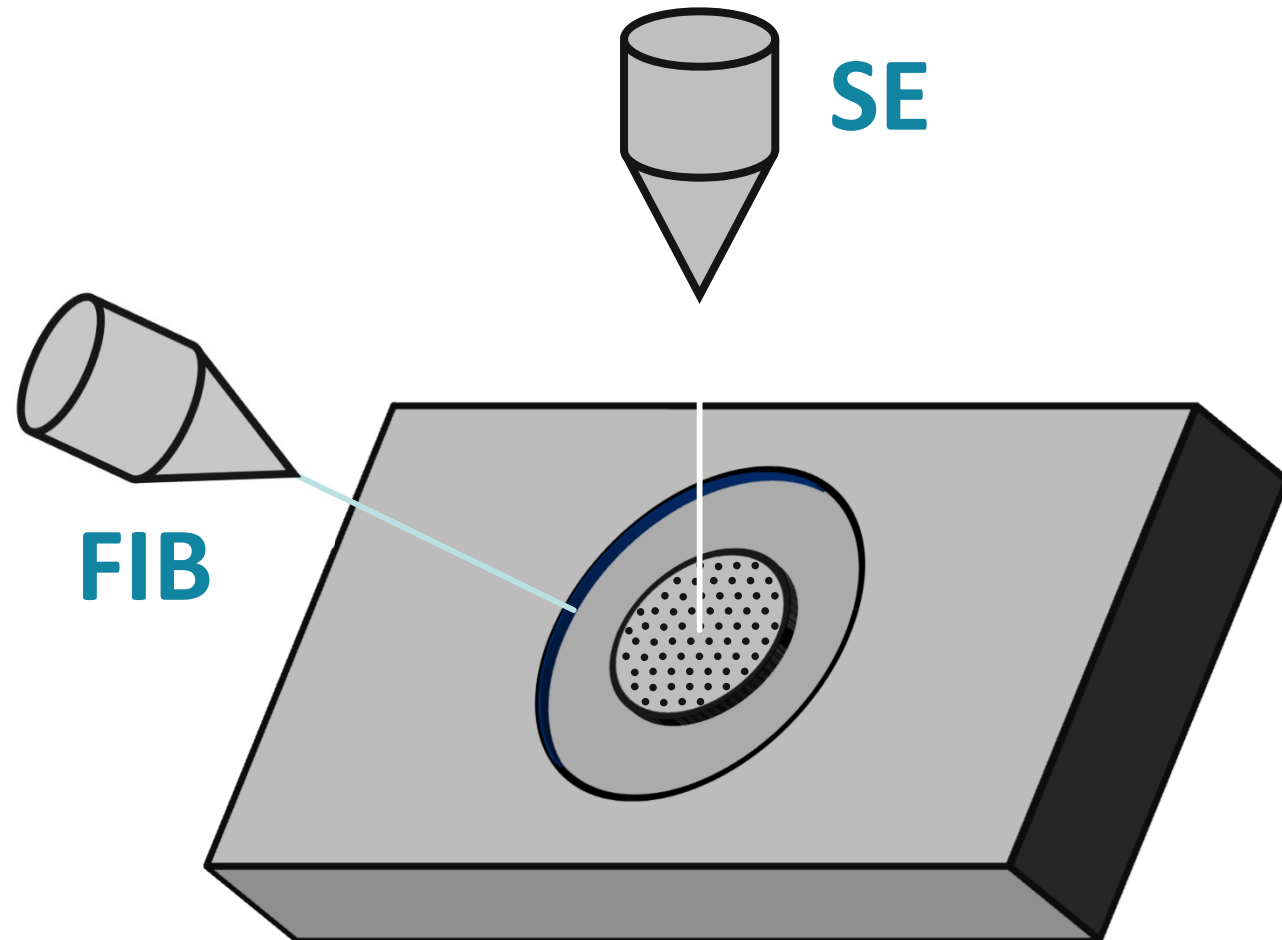
*A. M. Korsunsky et al., Surface & Coatings Technology 205 (2010) 2393–2403*

*M. Sebastiani et al, Materials and Design, vol. 118, pp. 204-206, 2017.*

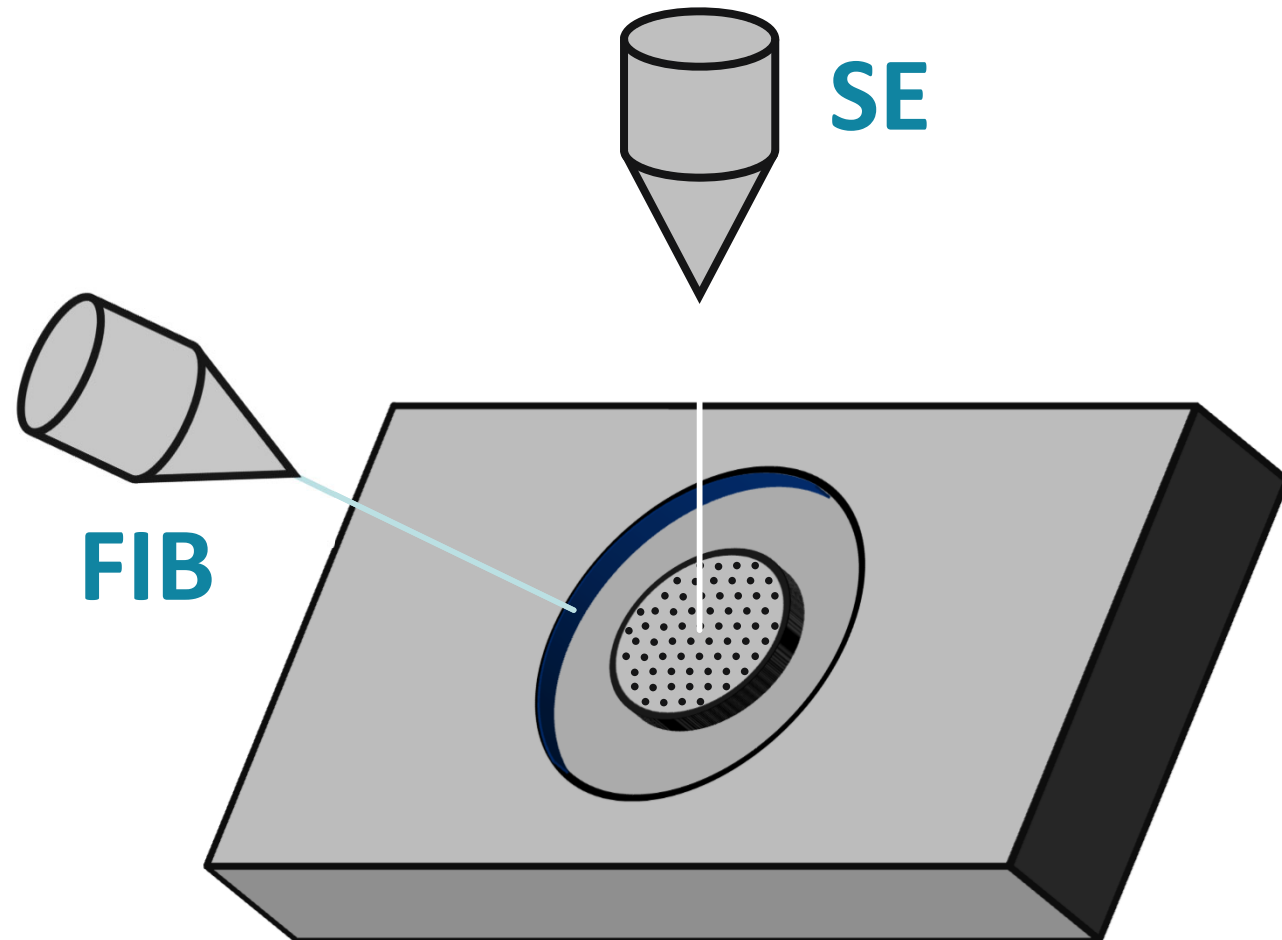
# Principles of ring-core milling



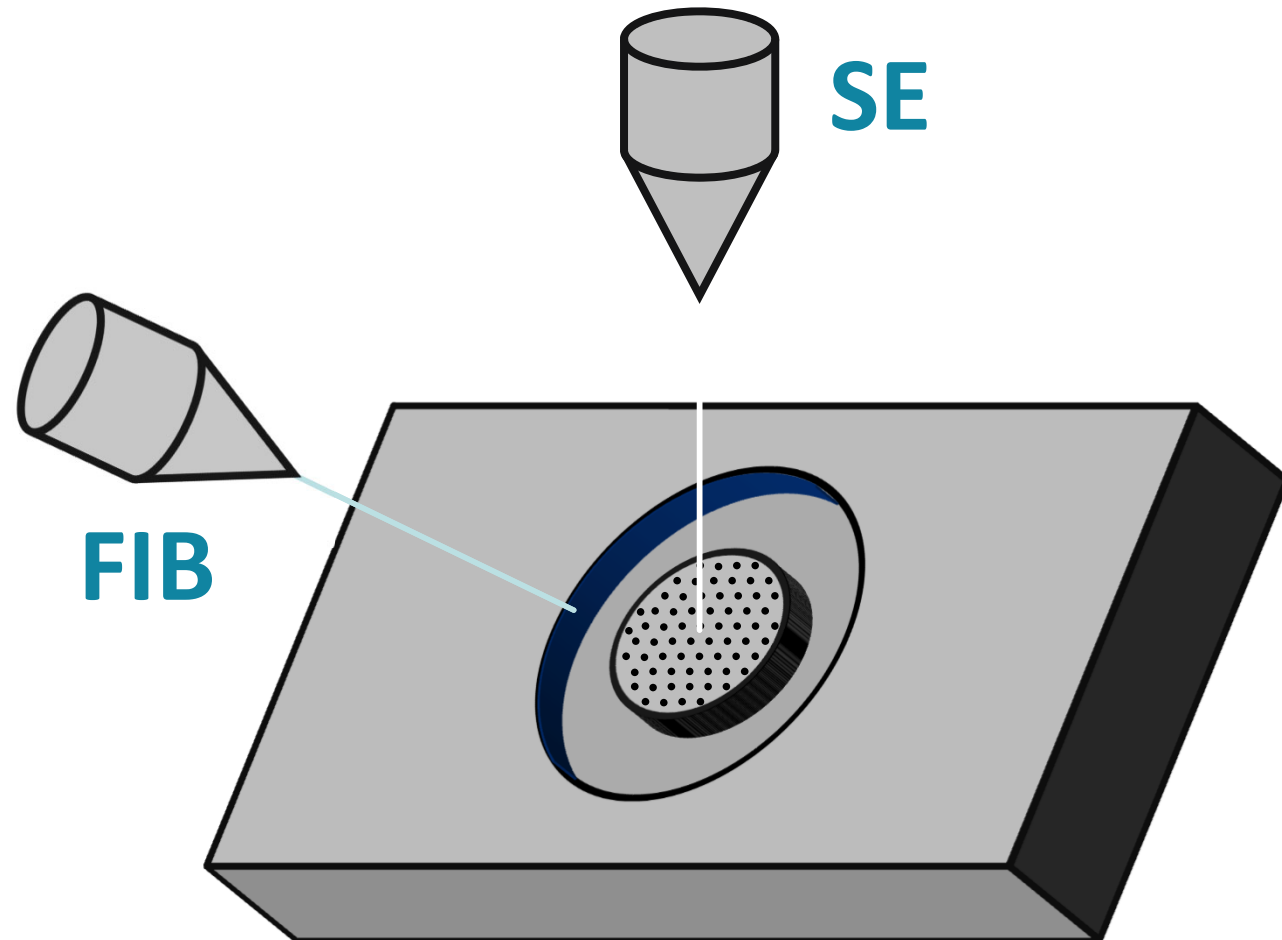
# Principles of ring-core milling



# Principles of ring-core milling



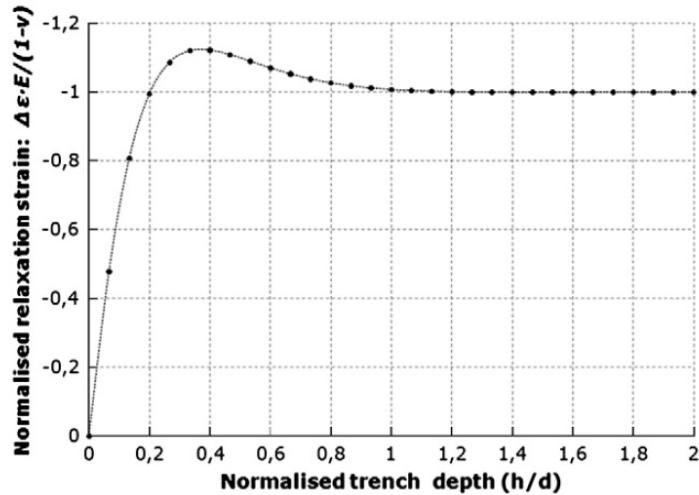
# Principles of ring-core milling



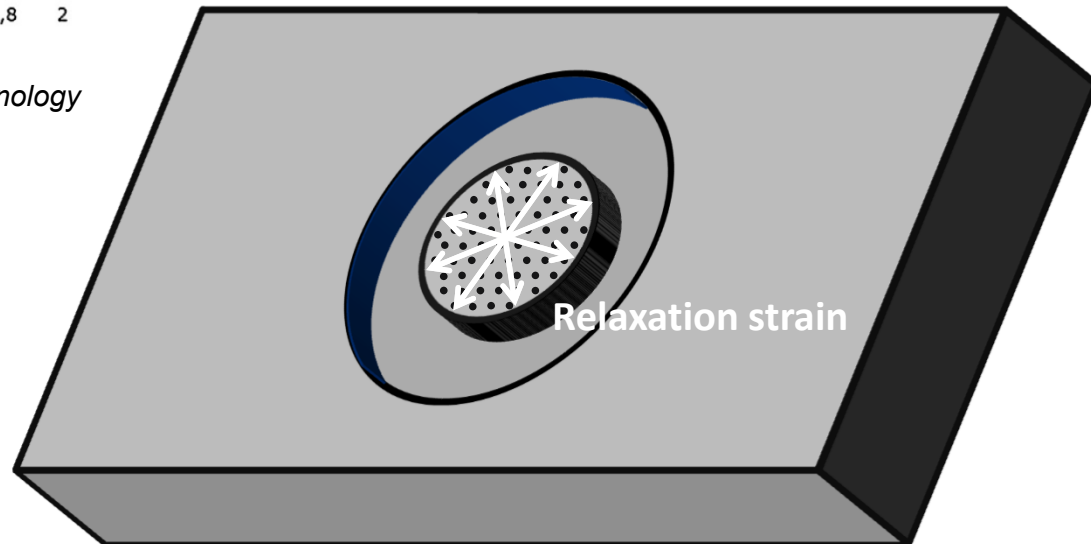


# Principles of ring-core milling

Modelling by continuum mechanics

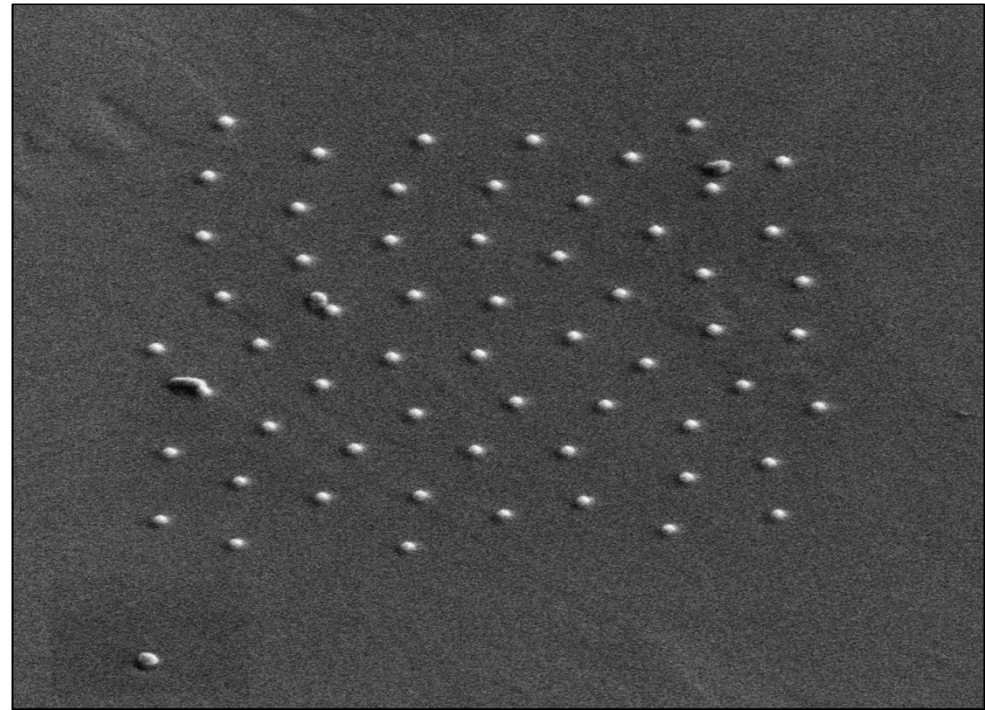
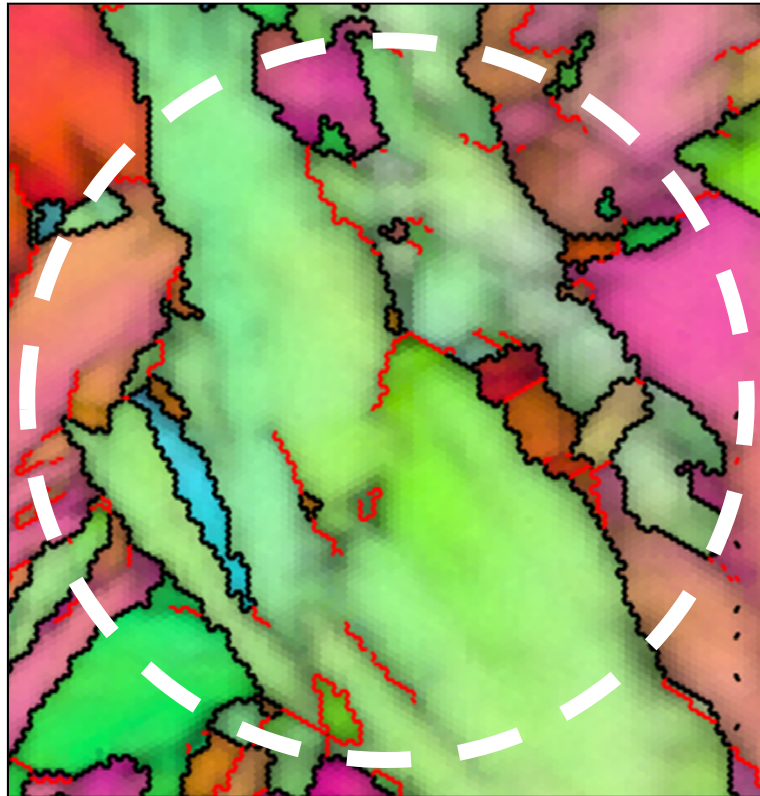


A. M. Korsunsky et al., *Surface & Coatings Technology* 205 (2010) 2393–2403

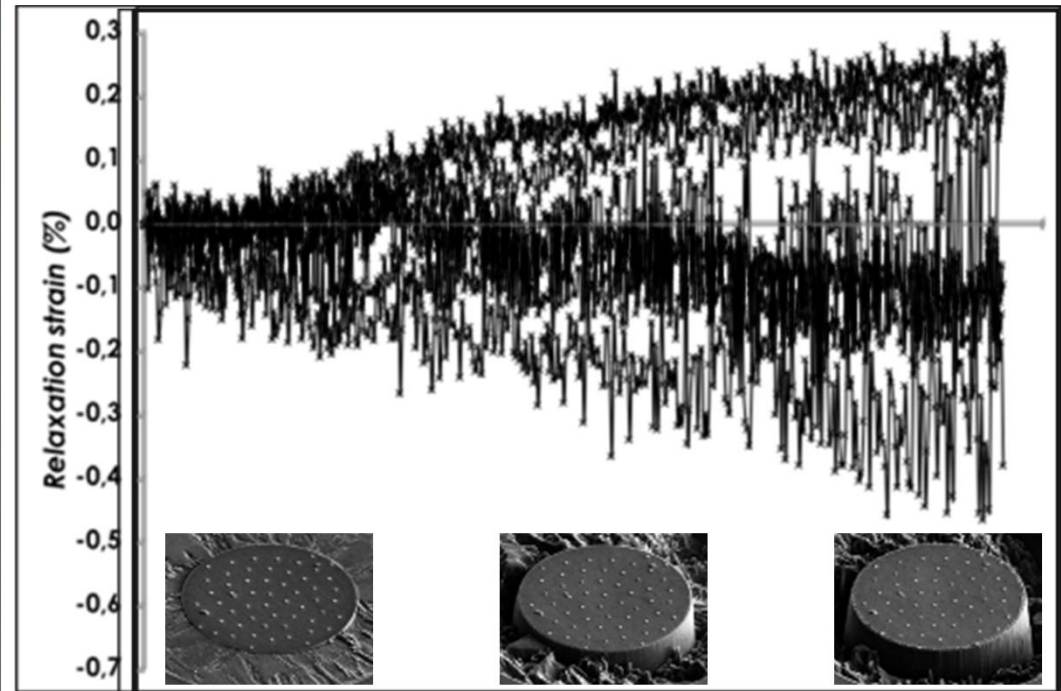
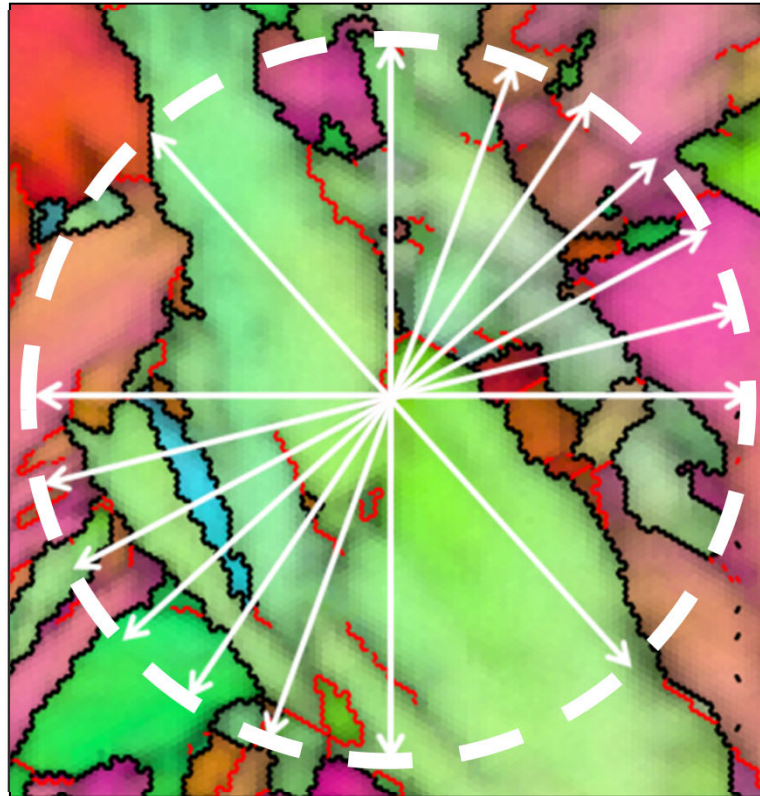


Full relaxation achieved when ring diameter equal ring depth!

# Measurement of relaxation strain

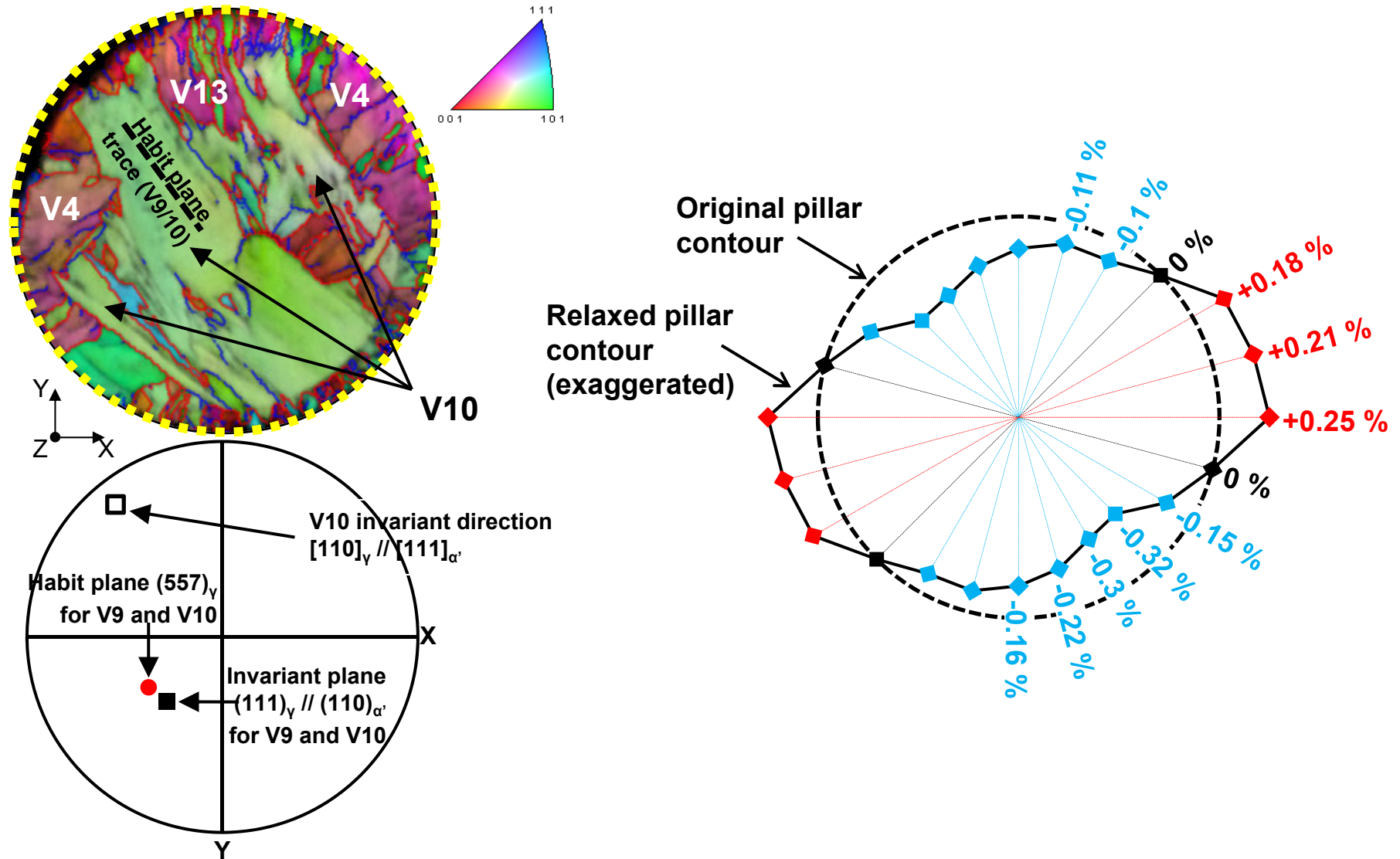


# Anisotropy of strain relaxations



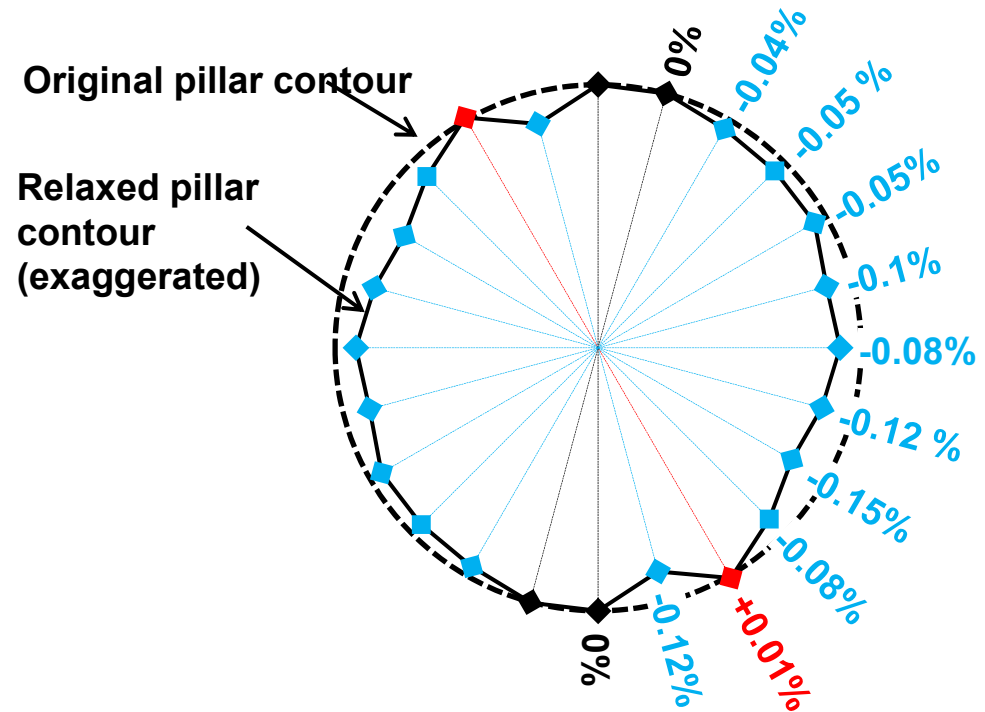
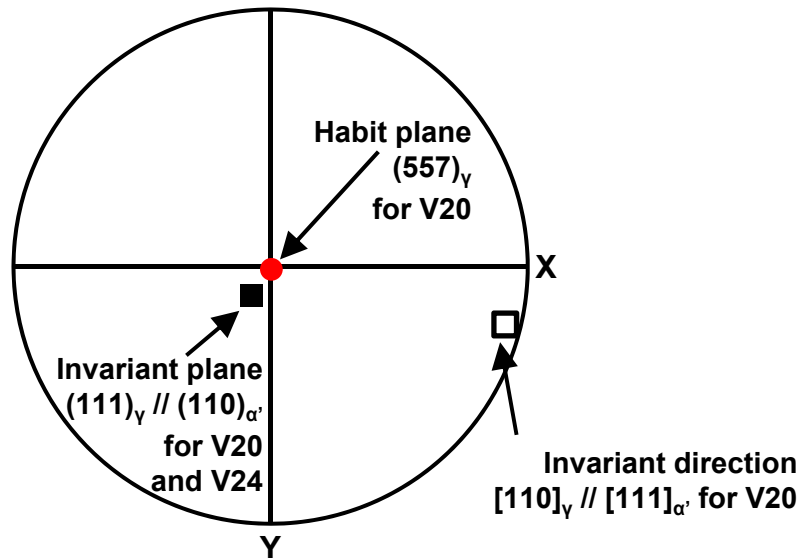
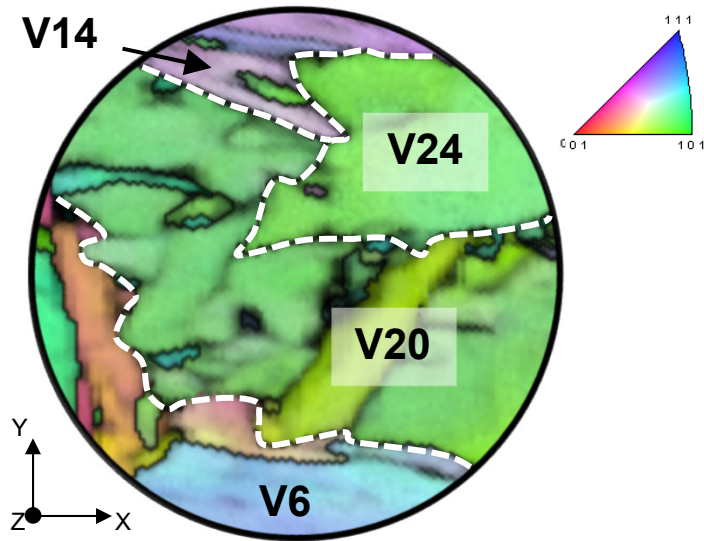


# Strain relaxation and crystallography



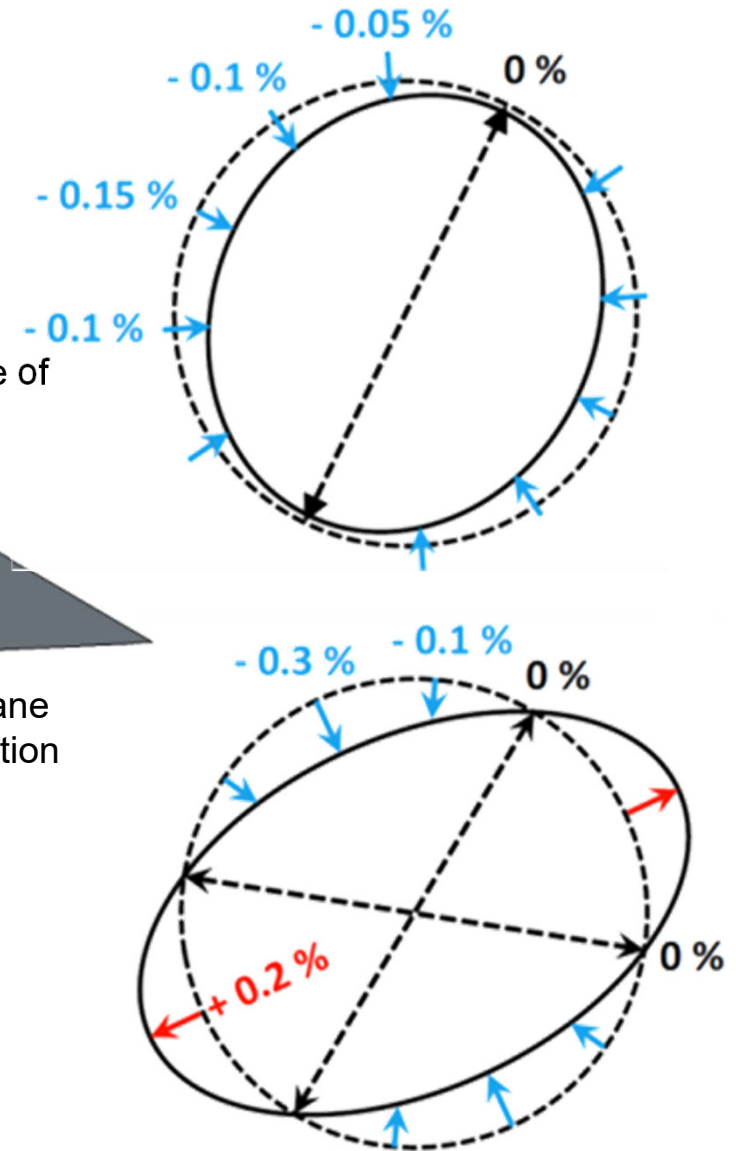
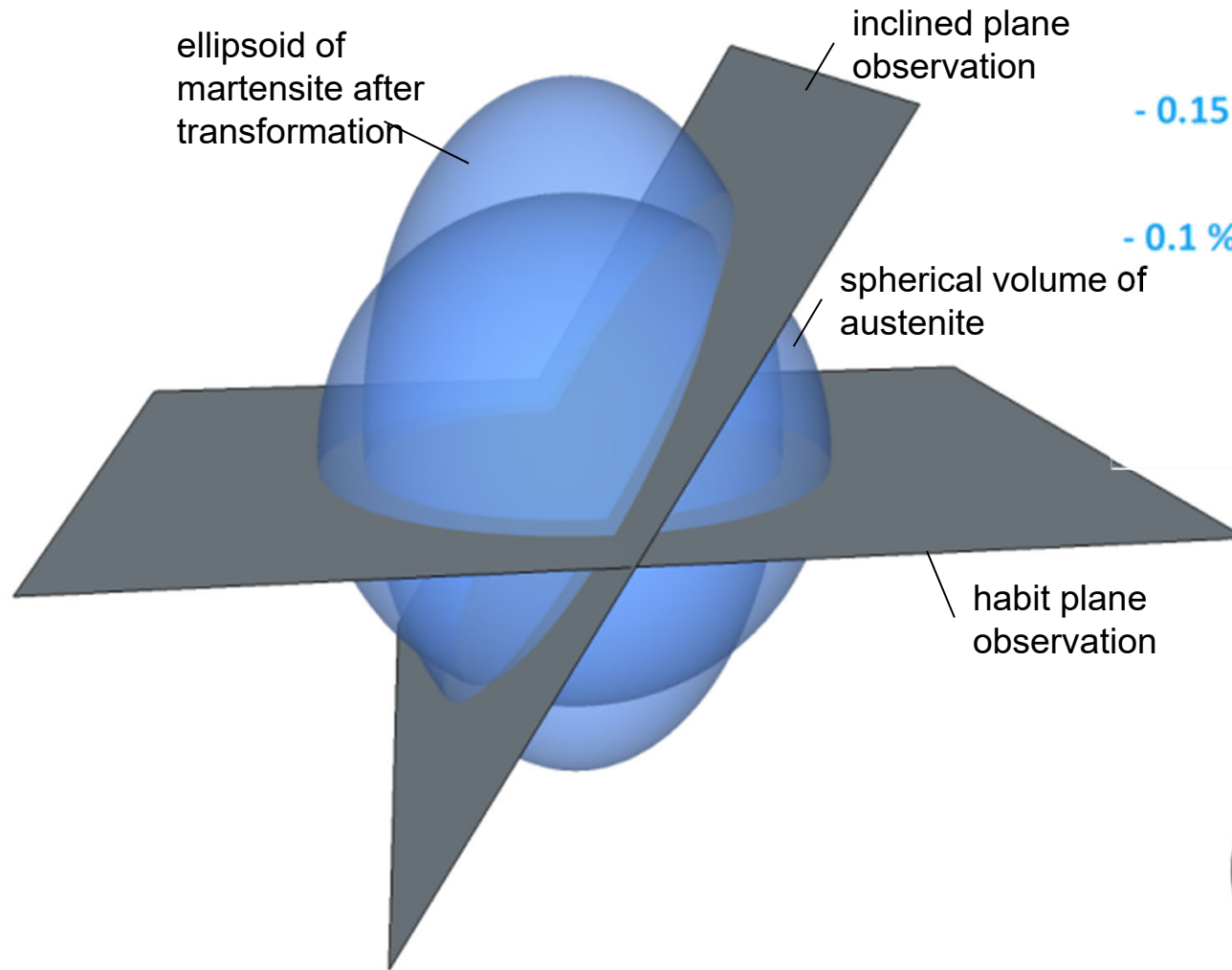


# Strain relaxation and crystallography





# 3-dimensional strain model



# RCM: pros and cons



- Absolute strain measurement possible
- Micron-resolution ( $\sim 5 \mu\text{m}$ )
- Creates its own reference at any place
- Applicable also to non-crystalline solids
- Laborious, time consuming process
- No mapping possible
- Tends to create artefacts during the imaging process
- Quality of DIC pattern determines quality of reference state

# Contents

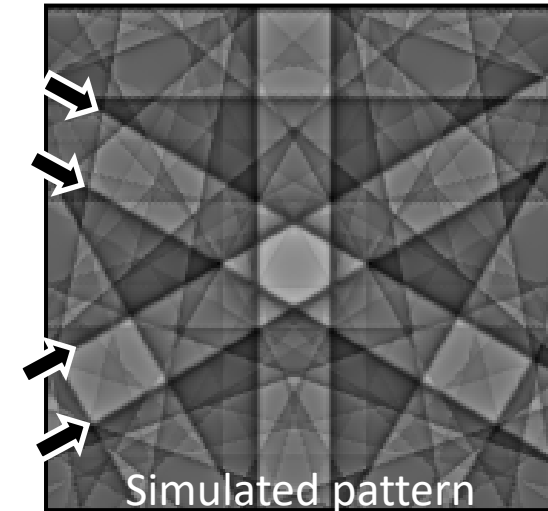
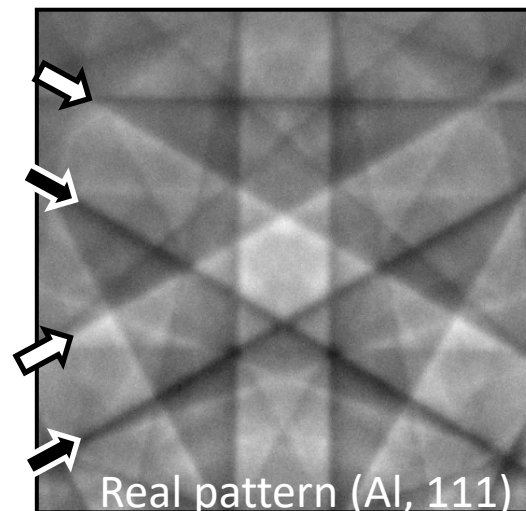
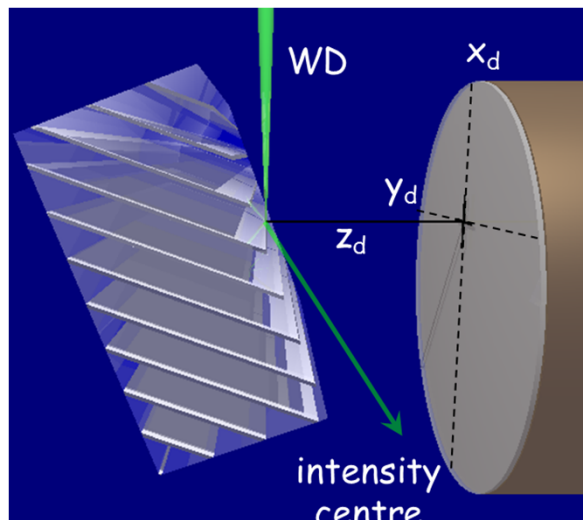


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# Absolute orientation measurements with EBSD

- What/where is the correct reference?
- For CC EBSD: Use a simulated diffraction pattern
  - What are the correct – relaxed – lattice constants?
    - Depends on local chemistry
  - How to obtain the correct pattern center?
  - How to deal with excess and deficiency lines?

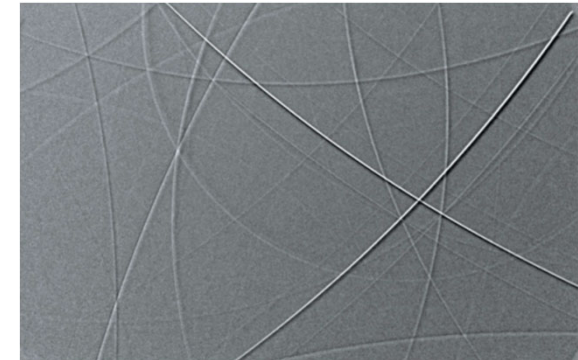


Create a fully relaxed local reference by ring core milling!

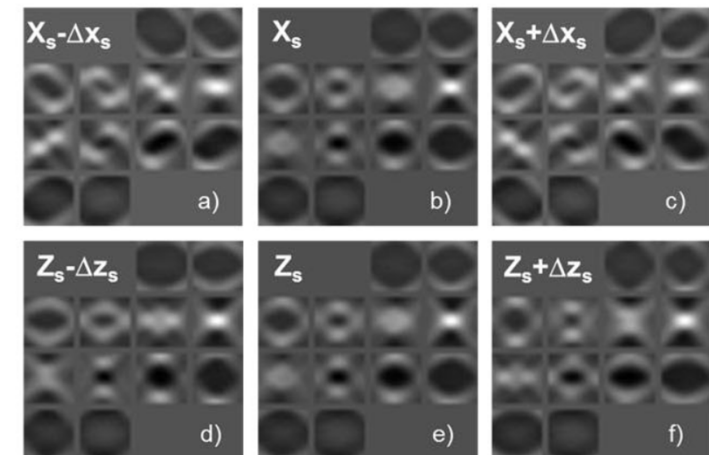
# Alternative measurement techniques



- micro-Kossel diffraction (*E. Langer, or D. Bouscaud et al, J. Appl. Cryst. 47, 1699*)
  - Highest possible strain accuracy ( $10^{-5}$ )
  - Absolute measurements possible
  - Mapping possible
  - Moderate spatial resolution ( $10\ \mu\text{m}$ )
  - Limited applicability (suitable x-ray wavelength required)

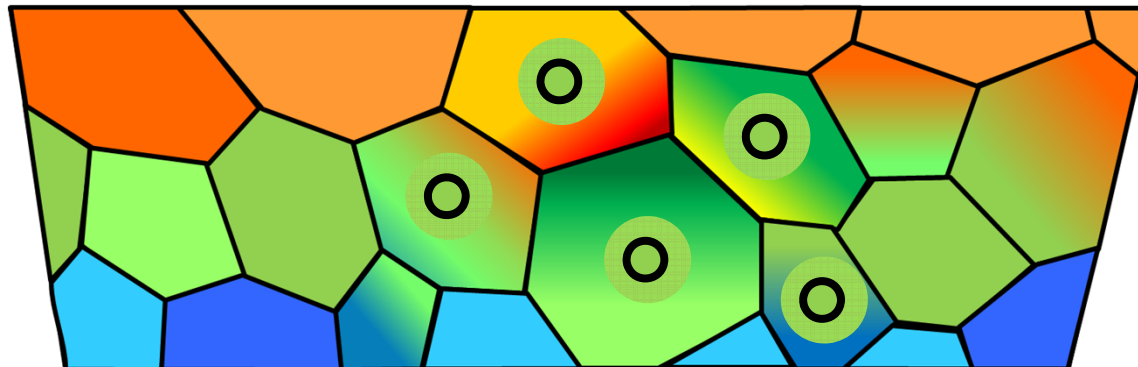


- 3D Hough transform (*Fortunier & Maurice, Microsc. Microanal. 19 (Suppl 2), 2013*)
  - High spatial resolution (50...500 nm)
  - Absolute measurements principlly
  - Moderate accuracy for absolute measurements
  - Pattern center accuracy sufficient?
  - 9 independent variables, but only 3 fitting parameters

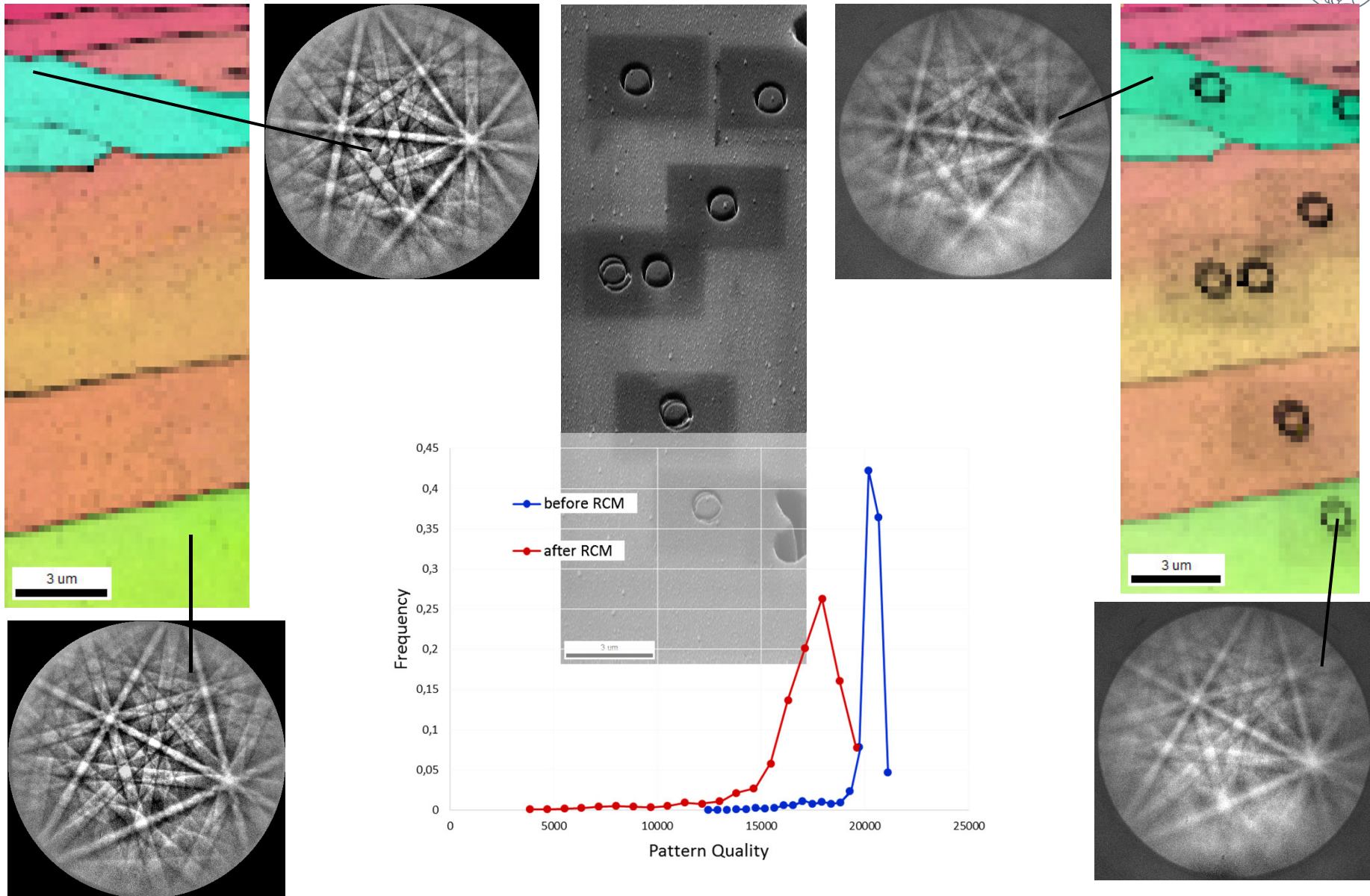


# Combination of RCM and CC EBSD – general principle

- Create a fully relaxed reference point by RCM at every relevant position
  - no need to perform DIC for RCM
  - use center of RCM as reference of CC EBSD
  - no need of accurate pattern center determination (linear extrapolation from reference pattern for every grain)
  - high resolution strain mapping possible



# RCM - CCEBSD Experimental procedure



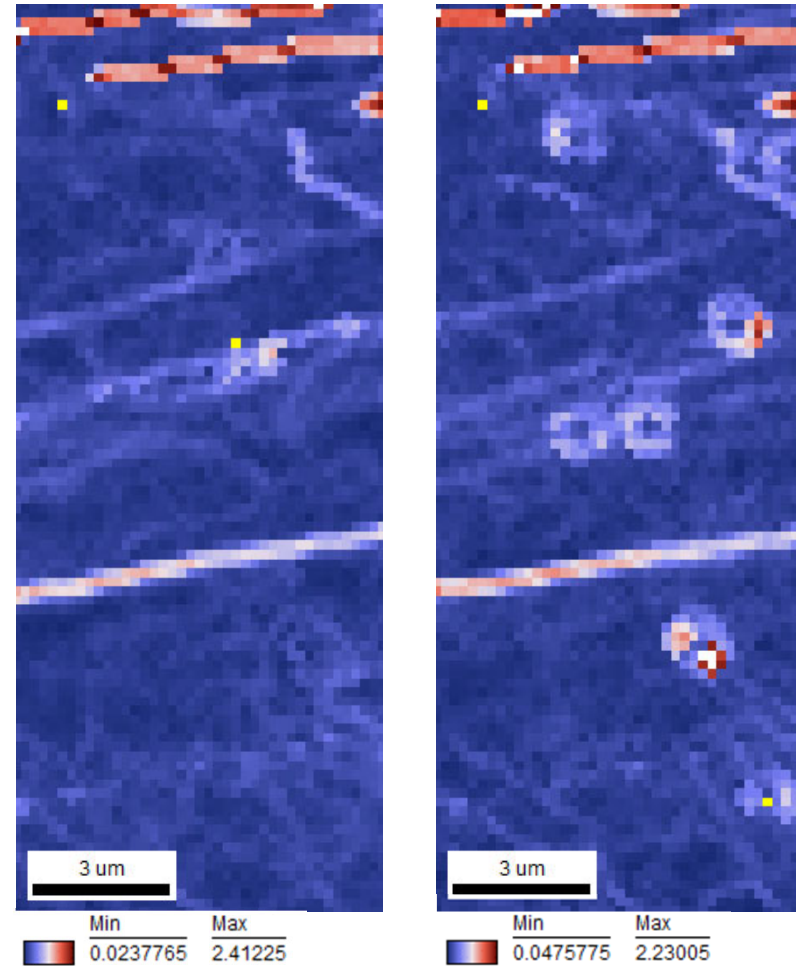
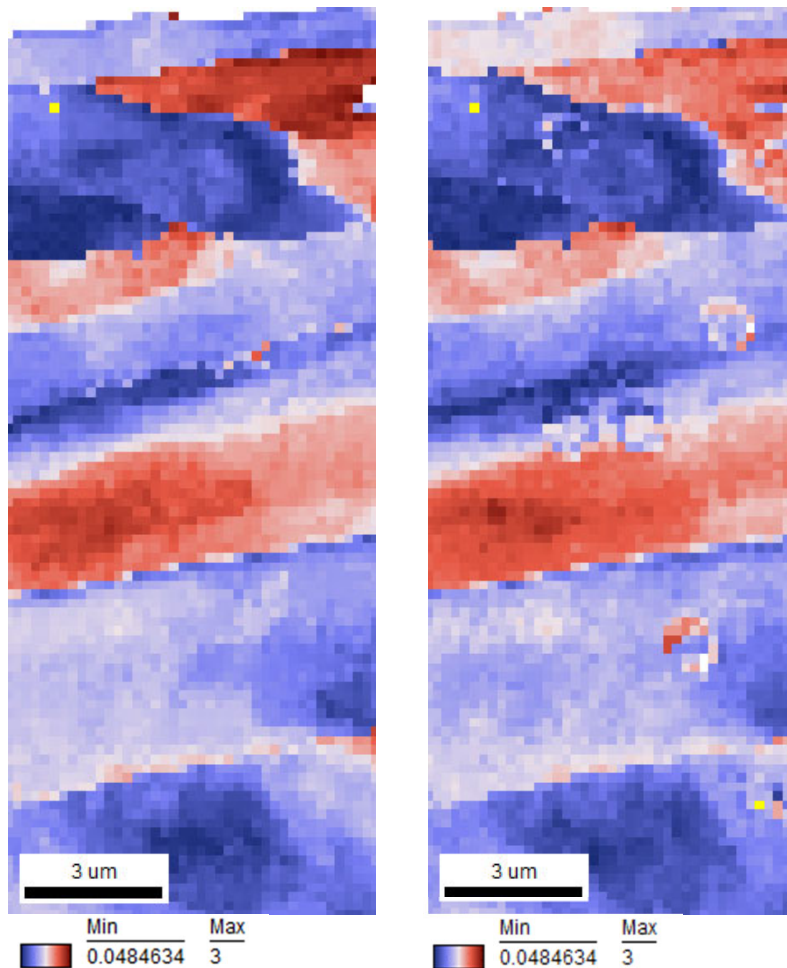
Reduction of pattern quality due to extensive electron observation

# Influence of milling on lattice defect density



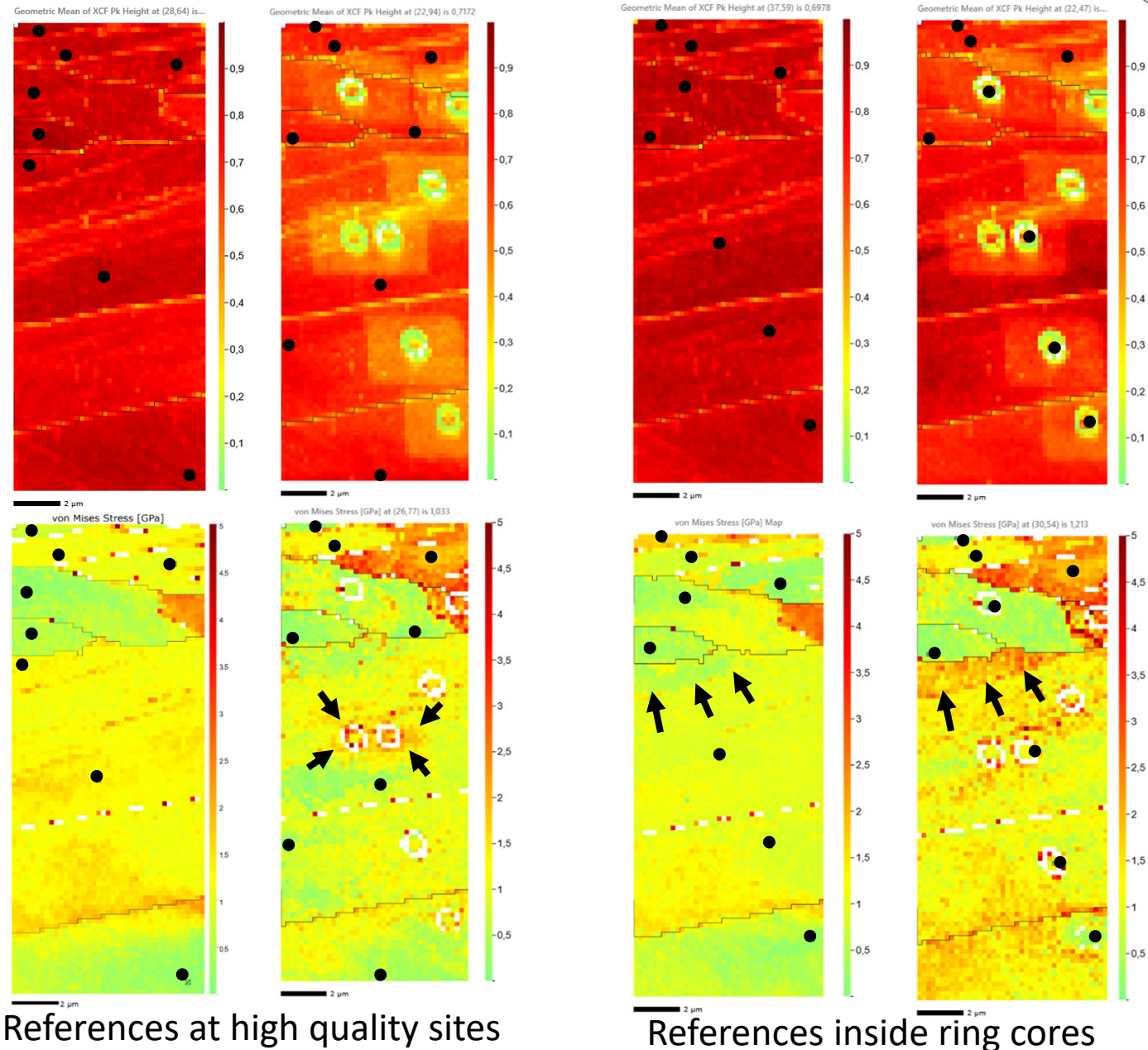
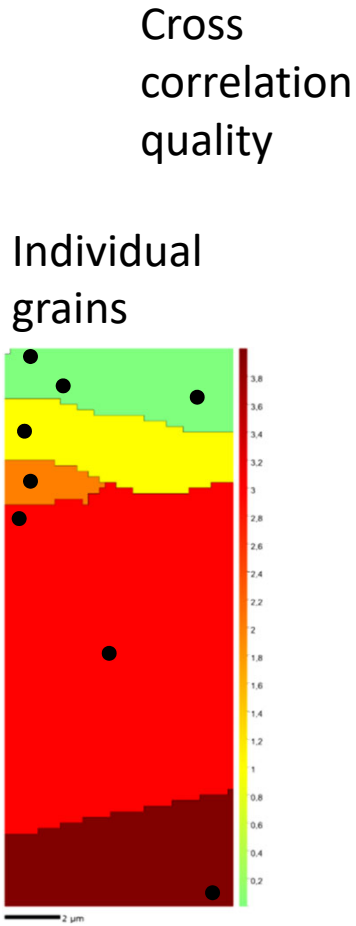
GROD

Local Orientation Spread

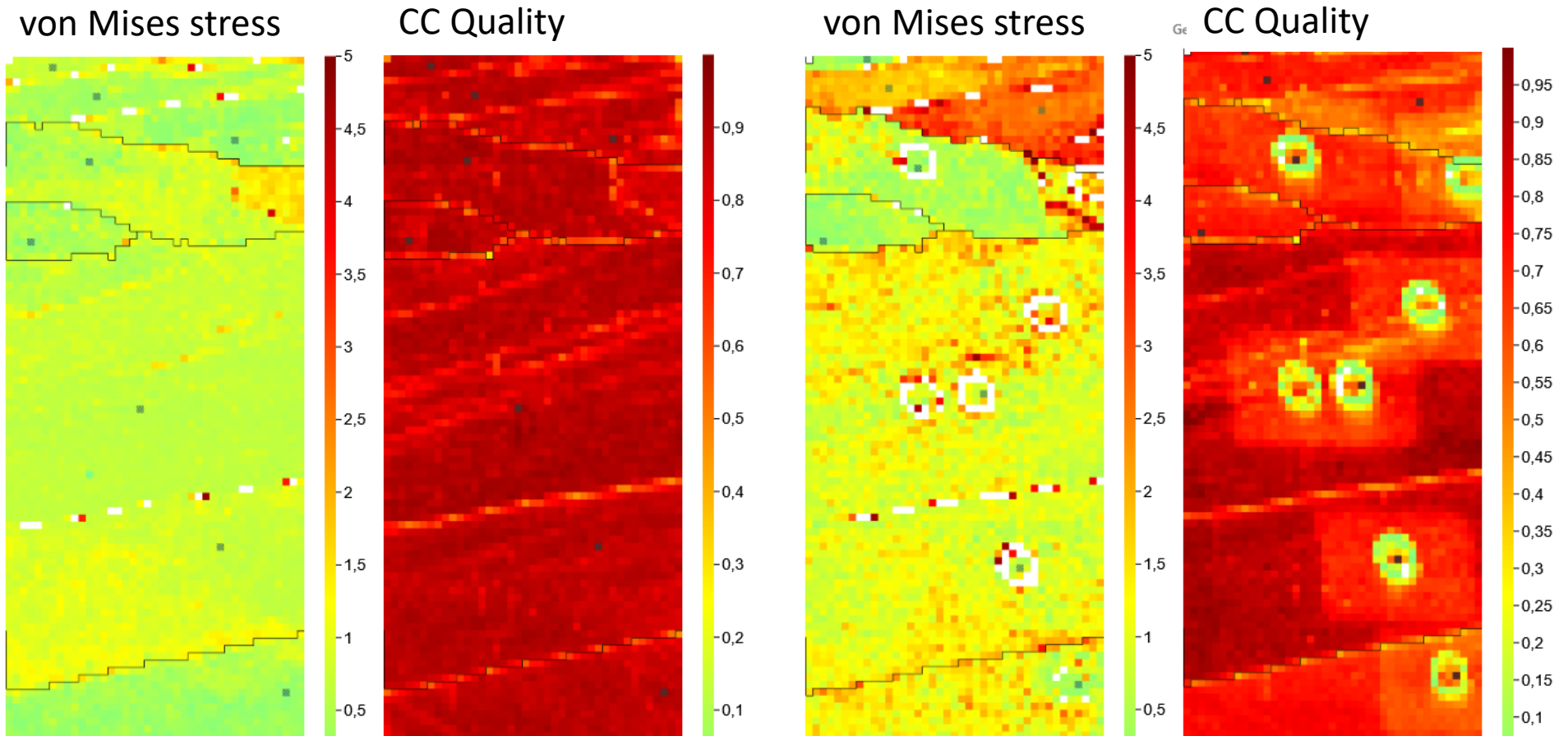


Influenced area larger than milling area, center of ring cores not affected  
Optimum ring size: 1.5...2  $\mu\text{m}$ , affected area not much larger than ring

# Reference patterns outside and inside of ring cores



# References in the ring cores with pattern remapping



- Current (preliminary) results: RCM references changes the stress state without affecting the lattice defect density
- 1st kind stress mapping is possible without further reference!
- Electron illumination must be kept minimum,
- ring diameter  $\sim 1.5 \mu\text{m}$  appears optimum



## RCM & CC EBSD: pros and cons (preliminary)

- 1st kind residual stresses are measured
- Internal references – no need to know cell parameters
- Mapping with EBSD resolution
- Much simpler procedure than RCM
- No scanning artefacts
- No need for accurate pattern center determination
- FIB instrument required
- More complicated and laborious than only CC EBSD
- Grain size must be larger than  $\sim 5 \mu\text{m}$

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# Conclusions

- Local residual stress measurements via CC EBSD
  - high lateral and stress resolution
  - only stresses of 3rd kind can be measured
- Ring core milling: very valuable local stress measurement method
  - 1st and 2nd kind stresses measured
  - lateral resolution 1  $\mu\text{m}$
  - strain resolution not fully established
- RCM & EBSD: the best of both worlds!
  - 1st, 2nd and 3rd ind stresses are measured
  - lateral resolution 0.1  $\mu\text{m}$ , strain resolution  $10^{-4}$



# IMC20

## The 20th International Microscopy Congress

10-15 September 2023, BEXCO, Busan, Korea

### Key Dates

### Conference Begins in

### Links

#### AS-09 Advances in scanning electron microscopy and focussed ion beam microscopy ×

This symposium aims to address issue Scanning electron microscopy (SEM) is the most common and established electron microscopy technique. Reasons for this are its enormous versatility of observation techniques enabling the study of a vast amount of materials and material states, its high degree of automation, and its relative ease of operation. SEM based techniques span observation of materials from soft biological matter all the way to metals, semiconductors, minerals and ceramics. They cover high resolution imaging with secondary electrons, spectroscopic methods like x-ray spectroscopy for elemental composition measurement, Raman spectroscopy for strain measurements, cathodoluminescence for opto-electronic property measurements and diffraction techniques like electron backscatter diffraction (EBSD) techniques and electron channelling contrast imaging (ECCI) for the investigation of crystalline matter.

The focussed ion beam (FIB) scanning microscopes are usually built in combination with SEMs although they display an independent class of instrumentation. Mostly FIBs are used for target preparation of samples for transmission electron microscopy and atom probe tomography where one profits of simultaneous observation and analysis with the joint SEM. Nevertheless, they are also used for micromachining of samples for SEMs (e.g. for local mechanical testing) or for exposing features for further investigation with SEM e.g. by serial sectioning to perform 3D materials analysis. The combination with mass spectroscopy also allows high resolution elemental analysis. Lately the combination of FIB and SEM with laser beams enables the controlled removal of large amounts of material which offers further powerful preparation and investigation means.

